

TEMPERATURE-CONTROLLED PURGE GATE VALVE FOR CHEMICAL VAPOR DEPOSITION CHAMBER

FIELD OF THE INVENTION

The invention disclosed herein comprises methods for substantially preventing the formation of unwanted materials on an isolation valve fixture within a chemical vapor deposition (CVD) reactor. In a preferred embodiment, the invention provides apparatus and methods for limiting deposition/condensation of GaCl₃ and reaction by-products on an isolation valve.

BACKGROUND OF THE INVENTION

Group III-V compounds are important semiconductor materials useful for fabricating optic components (particularly, short wavelength LEDs and lasers) and electronic components (particularly, high-temperature/high-power transistors). However, the commercial exploitation of these III-V compounds has been hindered by the practical impossibility of directly growing bulk single crystal substrates of these substances. As most of these materials are therefore manufactured by heteroepitaxial CVD processes, their commercial exploitation has also been hindered by lack of practical epitaxial substrates for growth of low-defect density, monocrystalline layers of III-V compounds.

In the case of III-nitrides, one state-of-the-art approach to improving the quality of heteroepitaxially-grown material is to grow very thick layers. It has been discovered that, even though the lower portions of a thick layer may have excessive defect densities, the upper portions can nevertheless have adequate defect densities. However, growth of thick layers requires growth rates currently achievable only with hydride (halide) vapor phase epitaxy (HVPE). HVPE processes are conducted in CVD reactors, use precursor gases including corrosive chlorine compounds, and are conducted with a substrate at significantly elevated internal temperatures so as to promote a desired reaction between the precursor gases.

However, not all internal reactor components need be maintained at the high reaction/deposition temperatures, nor is it desirable to do so. For example, the walls of the CVD reactor chamber can be maintained at lower temperatures in order to limit unwanted deposition of target material on the reactor walls. Also, certain components within the reactor, e.g., o-rings, seals, gaskets, and the like, should be maintained at lower temperatures because they are often made of polymeric materials which can be damaged by higher temperatures.

On the other hand, it is also not desirable for internal components to be at too low a temperature. For example, precursor gases or reaction products can condense on internal

components at lower temperatures. Also, internal components at lower temperatures can cause undesirable interactions, such as complex formation, between the gases present in the reactor. Such effects can damage internal components and cause contamination of a growing semiconductor wafer.

5 Certain components can be both exposed to the interior of a reactor chamber and include temperature-sensitive materials, e.g., polymeric seals, and such components can be subject to the conflicting requirements, being at both higher and lower temperatures. Examples of such components (with conflicting temperature requirements) present in many commercial CVD reactors are gate valves (or load locks or transfer doors, or the like). Such commercial reactors often feature automated transfer of wafers between the interior of the reactor chamber and an intermediate environment known as a transfer chamber (or load chamber or transfer chamber, or the like). Such automated transfer means usually include an automated gate valve which, when open, accommodate wafer transfer and the automated wafer transfer devices, and which, when closed, seal the interior of the chamber from the exterior.

10 Briefly, when closed, at least a face of a gate valve is exposed to the reactor-chamber interior, and the temperature of the exposed face should be high enough so that described undesirable condensation/ reaction is limited. Also, when closed, the face of a gate valve should form a seal with an external face of the reactor, and the temperature in the vicinity of this must be low enough so that damage to sealing materials, e.g., gaskets, o-rings, and the like, is limited. Preferably, any thermal damage to the sealing materials is sufficiently low so that the gate valve can be opened and closed many thousands times without repair.

20 In the particular case of HVPE growth of GaN, a gate valve (or the isolation valve) assembly can be exposed to process gases including GaCl₃, NH₃, HCl, N₂, H₂ and Ar and to reaction products and by-products including NH₄Cl. Of these, the more problematic are the precursor gas GaCl₃ and the reaction product NH₄Cl. GaCl₃ is corrosive and can condense on surfaces below $\approx 80^\circ\text{C}$. NH₄Cl can condense on any surface inside the reaction chamber which is less than 150°C . Further, only a limited number of sealing materials are sufficiently resistant to corrosive chlorine-containing gases, and these generally cannot withstand temperatures in excess of $\approx 150 - 160^\circ\text{C}$.

30 The prior art describes methods purporting to protect reactor components from corrosive materials and to prevent condensation on cooler reactor components. For example, US 6,071,375 teaches protecting an internal component in a reactor by arranging it in a

recessed pre-chamber that is open to the reactor but kept relatively free of process gases by an inert purge gas stream injected into the pre-chamber. However, such arrangements involving pre-chambers would be cumbersome for high volume manufacturing equipment which generally has stringent size limitations. Also, US 6,086,673 teaches a two zone, hot-wall reactor. In a precursor production zone, the temperature is of the order of 850 °C, whilst in a growth zone, the temperature is of the order of 1050 °C. However, hot wall reactors are inappropriate for high volume manufacturing processes because nitride deposition on the hot walls necessitates frequent chamber cleaning. Also, the problem of sealing an automated gate valve is not addressed here. US 5,156,521 illustrates an exemplary prior art gate valve.

The prior art is lacking in sealing methods and gate valve apparatus for a CVD chamber suitable for use in high volume manufacture of semiconductor materials, especially high volume manufacture of III-nitride and GaN materials.

SUMMARY OF THE INVENTION

According to a first aspect of the present invention, there is provided a method for forming a monocrystalline Group III – V semiconductor material comprising: reacting an amount of a gaseous Group III precursor as one reactant with an amount of a gaseous Group V component as another reactant in a reaction chamber under conditions sufficient to manufacture the semiconductor material, introducing the reactants so that they react at a predetermined location in the reaction chamber adjacent and above one or more substrates to deposit semiconductor material thereon, and injecting one or more purge gas streams to assist in directing at least one of the reactants to the predetermined location.

The gaseous Group III precursor may be continuously provided at a mass flow of at least 50 g Group III element/hour for a time of at least 48 hours.

The Group III precursor and Group V component are introduced into the reaction chamber in a controlled manner to react at the predetermined location adjacent and above one or more substrates to deposit the monocrystalline semiconductor material thereon. The reaction chamber is generally configured as a horizontal rectangular chamber and the method further comprises introducing the reactants through different portions of the chamber to avoid reacting until they reach the predetermined location adjacent and above the substrate(s).

More particularly, the reaction chamber may include a floor, a ceiling, a pair of sidewalls, an open inlet and an open outlet, and the method further comprises introducing one reactant through the floor of the chamber while introducing the other reactant through the inlet in combination with the one or more purge gas streams, to direct the other reactant to the predetermined location to efficiently deposit the monocrystalline material on the substrate(s). When one reactant may be introduced through a slot in the floor of the chamber, the other

reactant may be introduced at or near the inlet and which further comprises providing a gate valve in the reaction chamber inlet through which the purge gas stream(s) pass to enter the chamber and at least direct the other reactant to the predetermined location. The reactant that is introduced through the floor of the chamber is preferably the gaseous Group III precursor and the other reactant that is introduced through the inlet is preferably the Group V component, with a plurality of the purge gas streams provided to assist in directing the Group III precursor to the predetermined location.

The reaction chamber is generally made of quartz, and the gate valve is made of metal, so that the method further comprises providing an O-ring between the gate valve and reactor, and cooling the gate valve to avoid deteriorating the O-ring during operation. Also, the reactants are preferably provided as horizontal laminar flows in the reaction chamber and the plurality of gas streams introduced through separate apertures in the gate valve. For this, the apertures are advantageously provided in spaced relation in a face of the gate valve with the spacing between the apertures in a central portion of the face being greater than the spacing in other portions of the face.

When the gaseous Group V component is a nitrogen containing component, it is provided in a substantially greater amount than that of the gaseous Group III precursor so that a monocrystalline Group III nitride is provided. The Group III precursor may be gallium, aluminum or indium and the nitrogen containing component is a nitrogen containing gas such as ammonia or a nitrogen ion or radical generated by plasma-activation of nitrogen gas.

Embodiments of the invention also relate to a system for manufacture of a monocrystalline Group III-V semiconductor material. This system includes a source of a Group III precursor for use as one reactant, a source of Group V component for use as another reactant, a reaction chamber that receives the Group III precursor and Group V component for reaction therewith under conditions sufficient to form the monocrystalline Group III-V semiconductor material, and apertures for introducing the reactants into the reaction chamber so that they meet and react at a predetermined location and for injecting one or more purge gas streams into the reaction chamber to assist in directing at least one of the reactants to the predetermined location.

The reaction chamber is generally configured as a horizontal, rectangular chamber and the apertures for introducing the reactants are located in different portions of the chamber to avoid reaction until they meet at a predetermined location adjacent and immediately above the substrate(s). Also, as noted above, the reaction chamber includes a floor, a ceiling, a pair of sidewalls, an open inlet, an open outlet, and one reactant entry aperture comprises a horizontal

slot in the floor for introducing that reactant into the reaction chamber, with the slot configured and dimensioned to introduce the reactant and to direct it to the predetermined location for reaction with another reactant.

The system further comprises a rotatable support for holding one or more substrates upon which the monocrystalline semiconductor material is to be deposited, and the apertures allow introduction of the reactants into the reaction chamber in a controlled manner with the substrates and support configured, dimensioned and positioned with respect to the reactant entry apertures to facilitate formation and deposition of the monocrystalline semiconductor material upon the substrate(s). The entry aperture for the other reactant comprises an injection nozzle and at least one other aperture comprises a passage for introducing the one or more purge gas streams into the reaction chamber to direct the other reactant to the predetermined location to efficiently form the monocrystalline material on the substrate(s).

In a preferred embodiment, a gate valve associated with the inlet is provided for introducing the purge gas stream(s) in a manner that directs the other reactant to the predetermined location to efficiently form the monocrystalline material upon the substrate(s). The reactant that is introduced through the floor of the chamber is preferably the gaseous Group III precursor and the other reactant that is introduced through the inlet is preferably the Group V component, with the gate valve including a plurality of the apertures for introducing the purge gas streams into the reaction chamber to assist in directing the Group III precursor to the predetermined location.

The system typically provides the reactants to enter the reaction chamber as horizontal laminar flows with the plurality of purge gas streams enter through separate apertures in the gate valve. This can be achieved by providing apertures in spaced relation in a face of the gate valve with the spacing between the apertures in a central portion of the face being greater than the spacing in other portions of the face. When the reaction chamber is made of quartz and the gate valve is made of metal, an O-ring located between the gate valve and reactor may be included for providing a sealing connection. Also, the gate valve may be cooled by the purge gas stream(s) to avoid deteriorating the O-ring during operation.

Embodiments of the invention also relate to a method for forming a monocrystalline Group III – V semiconductor material by reacting an amount of a gaseous Group III precursor as one reactant with an amount of a gaseous Group V component as another reactant in a reaction chamber under conditions sufficient to manufacture the semiconductor material, where the reactants are introduced into the reaction chamber so that they react at a predetermined

location in the reaction chamber adjacent and above one or more substrates to deposit semiconductor material thereon and also injecting one or more purge gas streams to assist in directing at least one of the reactants to the predetermined location. Especially, this method continuously provides the gaseous Group III precursor at a mass flow of at least 50 g Group III element/hour for a time of at least 48 hours.

More particularly, the purge gas streams may be injected through a plurality of apertures in a gate valve that is closable to seal an inlet port of the reaction chamber and openable to allow transfer of materials between the reaction chamber interior and exterior through the inlet port. Portions of the gate valve adjacent to a seal between the gate valve when closed and the reaction chamber can be sufficiently cooled in order to avoid thermal deterioration of the seal during operation, e.g., cooled by passing cool fluids through passages that are conductively-coupled to the gate valve. Additionally, portions of the gate valve exposed to the reaction chamber interior when closed can be sufficiently heated in order to avoid condensation of and/or unwanted reaction between gases in the reactor while limiting the heating so as to avoid thermal deterioration of a seal between the gate valve when closed and the reaction chamber. The gate valve can be heated by passing a heated fluid through one or more passageways internal to the gate valve. Exemplary temperatures are greater than either or both of a condensation temperature of the Group III precursor and a sublimation temperature of a product of a Group III-Group V reaction.

According to a second aspect of the invention, there is provided a gate valve assembly configured to be used for reversibly sealing a material transfer port of a CVD reaction chamber, the assembly comprising: a gate valve that is closable to seal the material transfer port and openable to allow transfer of materials through the inlet port; and a temperature control that maintains gate valve temperatures in selected ranges of temperatures during reaction-chamber operation.

More particularly, the temperature control can include one or more heating elements, such as radiant-heating elements external to the gate valve or passages internal to the gate valve for heated fluids, for sufficiently heating the portions of the gate valve exposed to the reaction chamber interior when closed in order to avoid condensation of and/or unwanted reaction between gases in the reactor. When the gate valve assembly includes a seal between the closed gate valve and the reaction chamber, the temperature control preferably also includes further one or more cooling elements, such as one or more passages for cooled fluids that are conductively-coupled to the gate valve, for sufficiently cooling portions of the gate valve adjacent to the seal to avoid thermal deterioration of the seal during operation.

The gate valve also preferably provides a plurality of apertures configured to inject gas streams into the reaction chamber during operation. These apertures can either be in a spaced relation with the spacing between the apertures in a central portion being greater than the spacing of the apertures in other portions or in a spaced relation with the substantially uniform spacing between the apertures.

According to a third aspect of the present invention, there is provided a system for manufacture of a monocrystalline Group III-V semiconductor material, which comprises a source of a Group III precursor for use as one reactant; a source of Group V component for use as another reactant; a reaction chamber that receives the Group III precursor and Group V component for reaction therewith under conditions sufficient to form the Group III-V semiconductor material, the reaction chamber having apertures for introducing the reactants into the reaction chamber so that they meet and react at a predetermined location in the reaction chamber adjacent and above one or more substrates to deposit semiconductor material thereon, apertures for injecting one or more purge gas streams, and a loading port through which semiconductor materials can be transferred between the interior and exterior of the reactor; a gate valve assembly for sealing the loading port, the assembly comprising a seal between the gate valve and reactor and a temperature control for controlling the temperature of the gate valve so as to avoid both condensation of and/or unwanted reaction between gases in the reactor and also thermal deterioration of the seal.

The gate valve of the system preferably provides a plurality of apertures through which the purge gas streams are injected into the reaction chamber in a manner that at least partially directs one reactant to the predetermined location. And the temperature control preferably has one or more heating elements for sufficiently heating portions of the gate valve exposed to the reaction chamber interior when closed in order to avoid condensation of and/or unwanted reaction between gases in the reactor. The temperature control preferably has one or more cooling elements for sufficiently cooling portions of the gate valve adjacent to the to avoid thermal deterioration of the seal during operation, and one or more elements for sensing temperatures of the gate valve and for providing feedback to the temperature control.

The reaction chamber is configured arranged so that the reactants enter the reaction chamber as horizontal laminar flows. It is optionally further configured with a floor, a ceiling, a pair of sidewalls, an open inlet, an open outlet, and one of the reactant entry apertures is a horizontal slot in the floor for introducing that reactant into the reaction chamber, with the slot

configured and dimensioned to introduce the reactant and to direct it to the predetermined location for reaction with another reactant.

Further aspects and details and alternate combinations of the elements of this invention will be apparent from the appended drawings and following detailed description and these are also within the scope of the invention.

BRIEF DESCRIPTION OF THE DRAWINGS

The present invention may be understood more fully by reference to the following detailed description of the preferred embodiment of the present invention, illustrative examples of specific embodiments of the invention and the appended figures in which:

Fig. 1 illustrates schematically systems of the invention;

Figs. 2A-C illustrates preferred GaCl_3 sources;

Figs. 3A-C illustrates preferred reaction chambers;

Fig. 4 schematically preferred transfer/reaction chamber combinations;

Fig. 5 schematically illustrates preferred inlet manifold structures;

Fig. 6 illustrates schematically an alternative reactant gas inlet arrangement;

Fig. 7A-B illustrate preferred embodiments of gate valves; and

Fig. 8A-C illustrate further preferred embodiments of gate valves.

The same reference numbers are used to identify the same structures appearing on different figures.

DETAIL DESCRIPTION OF THE PREFERRED EMBODIMENTS

This invention provides equipment and methods for high growth rate and high volume manufacturing of Group III-V compound semiconductor wafers not hitherto possible. The equipment is capable of sustained production in that over periods of weeks or months production does not need to be shut down for maintenance. The equipment is capable of high-throughput production in that at least a wafer (or a batch of wafers) can be produced every one to four hours. The Group III-V compound semiconductor wafers so produced are suitable for fabrication of optical and electronic components, for substrates for further epitaxial deposition and for other semiconductor material applications.

In preferred embodiments, the equipment and methods are specifically directed to producing GaN nitride wafers, and such embodiments are the focus of much of the subsequent description. This focus is for brevity only and should not to be taken as limiting the invention. It will be appreciated that the preferred embodiments can readily be adapted to producing

wafers of other Group III nitrides, e.g., aluminum nitride, indium nitride, and mixed aluminum/gallium/indium nitrides, and to producing wafers of Group III phosphides and arsenides. Accordingly, producing semiconductor wafers or wafers of any of the III-V compound semiconductors are within the scope of this invention.

5 This invention can be particularly cost effective because particular embodiments can be realized by modifying equipment already commercially available for epitaxial deposition of Si. Thereby, focus can be on the elements and features that are especially important to GaN epitaxy while aspects related to high volume manufacturing, which are well developed in silicon technology, can be maintained. Also, the equipment of this invention is designed to
10 have a significant duty cycle so that it is capable of high volume manufacturing. Also, the invention provides for virtually 100% efficiency in the use of expensive Ga by recovering and recycling of Ga that is not actually deposited and is therefore exhausted from the reaction chamber equipment; with limited downtime needed. Also, the inventive process and apparatus include an economical use of Ga precursors.

15 The invention includes the use of a known low thermal mass susceptor (substrate holder) and lamp heating with temperature controlled reactor walls. The use of lamp heating permits the heat energy to mainly be coupled to the susceptor and not heat the reactor walls. The lamp heating system is equipped with a control system to permit very fast power changes to the lamps. The low thermal mass susceptor coupled with the lamp heating system permit
20 very fast temperature changes, both up and down. Temperature ramp rates are in the range of 2-10 degrees/second and preferably on the order of 4-7 degrees/second.

 The invention includes reactor walls that are controlled to a specific temperature to minimize undesired gas phase reactions and prevent deposition on the walls. The lack of wall deposition permits straightforward use of in-situ monitoring for growth rate, stress and other
25 pertinent growth parameters.

 The invention includes one or more external sources for the Group III precursor(s). The flow of the Group III precursor is directly controlled by an electronic mass flow controller. There is no practical limit on the size of the external Group III source. Group III source containers can be in the range of 50 to 100 to 300 kg, and several source containers
30 could be manifolded together to permit switching between containers with no down time. For the deposition of GaN, the Ga precursor is GaCl₃. This Ga source is based on the observations and discoveries that, when GaCl₃ is in a sufficiently low viscosity state, routine physical means, e.g., bubbling a carrier gas through liquid GaCl₃, can provide a sufficient evaporation

rate of GaCl_3 , and that GaCl_3 assumes such a sufficiently low viscosity state in a preferred temperatures of range of 100 to 130°C.

The invention includes equipment for maintaining the GaCl_3 at a constant temperature and pressure in the low viscosity state and equipment for flowing a controlled amount of gas through the liquid GaCl_3 and delivering the GaCl_3 vapor to the reactor. This equipment can sustain high mass flows of GaCl_3 (in the range of 200 to 400 g/hour) that result in GaN deposition rates in the range of 100 to 400 $\mu\text{m}/\text{hour}$ on one 200mm diameter substrates or any number of smaller wafers that fit on the susceptor. The delivery system from the GaCl_3 container is maintained with a specific temperature profile to prevent condensation of the GaCl_3 .

The invention also includes an inlet manifold structure that keeps the Group III and Group V gases separate until the deposition zone and also provides a method for achieving high gas phase homogeneity in the deposition zone, thus achieving a uniform flow of process gases into the reaction chamber and across the susceptor supporting the substrates. The process gas flow is designed to be substantially uniform in both flow velocity (therefore, non-turbulent) and chemical composition (therefore, a uniform III/V ratio). In a preferred embodiment, this is realized by providing separate primary inlet ports for the Group III and Group V gases that provide uniform distribution of gas across the width of the reactor, and to achieve high uniformity. In preferred embodiments, the manifold and port structures are designed and refined by modeling gas flows according to principles of fluid dynamics.

The invention also includes a method to add energy to either or both the Group III or Group V inlets to enhance the reaction efficiency of these precursors. In a preferred embodiment, this would include a method for thermal decomposition of the dimer form of the Group III precursor Ga_2Cl_6 into the monomer GaCl_3 . In another preferred embodiment, this would include a method for decomposition of the ammonia precursor, for example by thermal decomposition or plasma.

The invention also includes equipment for automated wafer handling, including fully automatic cassette-to-cassette loading, separate cooling stages, load locks, non-contact wafer handlers, all of which are fully computer controlled and interfaced to the overall growth program.

The invention also includes temperature control of the reactor inlet and outlet flanges and the exhaust system and a specially designed pressure regulating valve that can operate at reduced pressure and high temperatures. Temperature control in these areas prevents

premature gas phase reactions and minimizes deposits of GaN as well as various reaction byproducts. A major reaction byproduct is NH_4Cl . The temperature of the entire exhaust downstream of the reactor is controlled to prevent condensation of NH_4Cl .

5 The invention also includes a gate valve that opens to allow transfer of wafers between the interior of the reactor chamber and the exterior, and that closes to seal the interior of the reactor chamber from the exterior. The gate valve preferably includes a plurality of inlet ports, which, in preferred embodiments, are used to admit inert gases to control and reduce deposits on the valve material and the side walls of the reactor and to reduce gas recirculation and reduce residence time of the gases in the reactor. Preferably, at least the sealing face of
10 the gate valve is temperature controlled.

Additional aspects and details of the invention include the use of a susceptor that can hold one or more wafers during one growth run and a susceptor designed to prevent attachment of the substrate to the susceptor during thick growth runs.

The present invention is based on the discovery that specific metal halide compounds
15 have certain unique chemical properties, and that when coupled with an apparatus designed in light of these properties, the combination can be used to deposit thick layers of Group III-V compound semiconductors, and in particular gallium nitride, with heretofore unachievable high throughput, high uptime and low cost in a manner characteristic of high volume manufacturing.

20 For this invention, "high volume manufacturing" (or HVM) is characterized by high throughput, high precursor efficiency and high equipment utilization. Throughput means the number of wafers/hour that can be processed. Precursor efficiency means that a large fraction of the material input to the system goes into the product and is not wasted. Although there are a large number of variables associated with the material, process and structure, HVM
25 deposition rates range from around 50 g Group III element (such as gallium) per hour for a period of at least 48 hours, to 100 g Group III element per hour for a period of at least 100 hours, to 200 g Group III element per hour for a period of at least one week, to as much as 300 to 400 g Group III element per hour for a period of at least a month. A typical source capacity can range from 5Kg to 60 Kg in one vessel and for increased HVM, multiple vessels can be
30 operated in series. This can provide Group III-V material throughputs that are similar to those obtained in silicon manufacture.

Equipment utilization means the ratio of the time that the substrate is in the reactor compared to a given time period, such as 24 hours. For HVM, most of the time is spent

producing product as opposed to set-up, calibration, cleaning or maintenance. Quantitative ranges for these measures are available for mature silicon semiconductor processing technology. The equipment utilization for HVM of Group III-V material is on the order of about 75 to 85%, which is similar to that of silicon epitaxial deposition equipment.

5 Reactor utilization is the period of time during which growth of the material on the substrate is occurring in the reactor. For conventional HVPE reactors, this value is on the order of 40 to 45%, while for a HVM reactor such as those disclosed herein, this value is on the order of 65 to 70%.

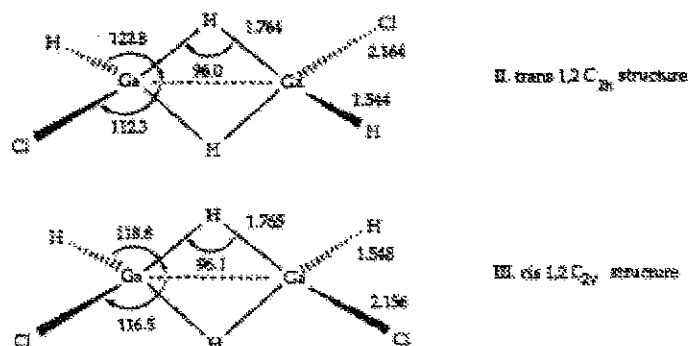
10 Growth utilization is the overhead time in the reactor, meaning that it is the time during which growth is occurring in the reactor after a substrate is provided therein. For conventional HVPE reactors, this value is on the order of 65 to 70%, while for a HVM reactor such as those disclosed herein, this value is on the order of 95% to close to 100%, i.e., close to that of a silicon manufacturing process.

15 The present invention addresses the main limitations of the current HVPE technology which prevent high volume manufacturing. This is done by replacing the current HVPE in-situ source generation with an external source and replacing the current HVPE high thermal mass hot wall reactor with a low thermal mass reactor with temperature controlled walls. The use of an external source eliminates the need to stop production to charge the precursors, greatly increasing the equipment utilization. Furthermore, the mass flux of the precursor is
20 controlled directly by an electronic mass flow controller, resulting in improved control of the growth process and improve yield. The low thermal mass reactor with temperature controlled walls greatly reduces the time required for heating and cooling, both during growth and maintenance. The ability to rapidly heat and cool the substrate also permits the use of multi-temperature processes, which are not practically possible in the current HVPE hot wall
25 system. The ability to control the wall temperature reduces gas phase reactions and almost completely eliminates wall deposits. Elimination of wall deposits greatly increases the time between cleaning, leading to high reactor utilization.

30 The present invention is based on the fact that certain metal halide compounds can be used as an external source for HVPE deposition of III-V compound semiconductors and can provide, in conjunction with specific delivery equipment detailed in this invention, a sufficiently high mass flux to achieve and maintain high deposition rates on large areas. In particular, when melted, GaCl₃ is in a sufficiently low viscosity state to permit routine physical means, e.g. bubbling with a carrier gas through liquid GaCl₃, can provide a sufficient

evaporation rate of GaCl_3 , and that GaCl_3 assumes such a sufficiently low viscosity state at temperatures in a range about approximately 130°C . Furthermore this invention is based on the fact that GaCl_3 , in the liquid phase and in the gas phase at temperatures below about 400°C is actually a dimer. The chemical formula for the dimer can be written either as $(\text{GaCl}_3)_2$ or Ga_2Cl_6 .

In addition to Ga_2Cl_6 related chlorogallanes can also be used as a Ga precursor. These compounds are similar to Ga_2Cl_6 but with H replacing one or more Cl atoms. For example monochlorogallane has the two bridge Cl atoms replace by H atoms. As shown below, the terminal Ga-bonded atoms can also be replaced by H (note that there is a cis and trans version of this compound). According to B.J. Duke *et al*, Inorg. Chem. **30** (1991) 4225, the stability of the dimer decreases with increasing chlorination of the terminal Ga-x bonds by 1-2 kcal/mol per Cl substitution and increases by 6-8 kcal/mol with each Cl substitution for a bridging H atom. Thus as the number of substituted Cl atoms decreases, the fraction of the monomer, at a given temperature, would decrease.



The growth of In- and Al-containing compounds can be achieved using substantially similar equipment but with the limitation that these sources are not as easily kept in a liquid state. InCl_3 melts at 583°C . While the present invention described for GaCl_3 may be modified to operate at temperatures above 583°C , this is practically quite difficult. An alternate approach is to heat the InCl_3 to a temperature below the melting point but where the vapor pressure is sufficient to achieve acceptable deposition rates.

AlCl_3 sublimates at 178°C and melts at 190°C and 2.5 atm. The present invention described for GaCl_3 can be modified to operate at higher than atmospheric pressure and temperatures above the melting point of AlCl_3 . Additionally, the alternate approach described above for InCl_3 , heating below the melting point to achieve a sufficiently high vapor pressure,

will also work. AlCl_3 also forms a dimer $(\text{AlCl}_3)_2$ in the liquid phase and in the gas phase at low temperatures.

Another main component of this invention is a low thermal mass reactor. The low thermal mass reactor with temperature controlled walls greatly reduces the time required for heating and cooling, both during growth and maintenance. The ability to rapidly heat and cool the substrate also permits the use of multi-temperature processes, which are not practically possible in the current HVPE hot wall system. The ability to control the wall temperature reduces gas phase reactions and almost completely eliminates wall deposits. Elimination of wall deposits greatly increases the time between cleaning, leading to high reactor utilization.

The low thermal mass is achieved by using what is traditionally called a cold wall system, but in this invention the wall temperature is controlled to a specific temperature. The current hot wall systems are heated by being enclosed in a furnace. In the new system, only the substrate holder and substrate are heated. There are many ways to achieve this including lamp heating, induction heating or resistance heating. In one embodiment, the system consists of a reactor chamber constructed from quartz and a substrate heater constructed of graphite. The graphite is heated by lamps on the outside of the quartz reactor. The quartz reactor walls can be controlled using a variety of methods. In most cases the wall temperature control system consists of one or more methods to measure the wall temperature in a variety of locations, combined with a feedback system to adjust either cooling or heating input to the wall region to maintain the temperature at a preset value. In another embodiment, the wall temperature is controlled by fans that blow air onto the exterior of the reactor walls for cooling. The wall temperature is not constrained to be constant at all times; the temperature controller can be programmed to vary the temperature to achieve improved performance either during growth or maintenance.

Although the focus of the following description is primarily on preferred embodiments for producing gallium nitride (GaN) wafers, it will be appreciated that the equipment and methods described can be readily adapted by one of average skill in the art to also produce wafers of any of the III-V compound semiconductors are within the scope of this invention. Accordingly, such equipment is within the scope of the invention. Headings are used throughout for clarity only and without intended limitation.

Also the invention provides equipment for high volume manufacturing of GaN wafers that is economical to construct and operation. Preferred embodiments of the invention can be economically realized/constructed by adapting/modifying existing VPE equipment that has

been designed for and is commercially available for silicon (Si) epitaxy. To practice this invention, it is not necessary to undertake an expensive and time consuming process of designing and constructing all components for GaN deposition equipment from scratch. Instead, sustained, high-throughput GaN deposition equipment of the invention can be more rapidly and economically realized/constructed making targeted and limited modifications to existing Si processing production proven equipment. Along with such modified existing equipment, however, the invention also encompasses de novo construction.

Accordingly, the following description is first directed to the generally preferred features to be incorporated into existing Si equipment for GaN production. Features that can be retained from Si processing are not described in details as they are well known in the art. In different embodiments, different ones of the features to be described can be implemented; the invention is not limited to embodiments implementing all these features. However, for higher levels of sustained, high-throughout production, most or all of these features are advantageous and they include cassette to cassette loading, load locks and fully automated wafer handling with separate cooling stage which allows fast loading and unloading and processing a wafer while the other one is cooling. The loadlocks eliminate undesirable exposure of the reactor to atmosphere to minimize introduction of oxygen and water vapor and greatly reduce purge/bake time before running. Moreover the automated handling reduces yield loss and wafer breakage from manual handling of wafers. In some cases a Bernoulli wand is used to handle the wafers which allows hot loading and unloading at temperature as high as 900°C and save long cooling time.

General embodiments of the preferred features of this invention are first described in the context of a generic VPE system. It will become apparent how these general embodiments can be routinely adapted to particular, commercially available, Si epitaxy equipment. The following description is then directed to a particular preferred embodiment of this invention and of its preferred features that is based on one of the EPSILON® series of single-wafer epitaxial reactors available from ASM America, Inc. (Phoenix, AZ). It is apparent, however, that the invention is not limited to this particular preferred embodiment. As another example the inventions could easily be adapted to the CENTURA® series of AMAT (Santa Clara, CA).

Preferred embodiments of the equipment and methods of the invention (for producing GaN wafers) are described in general with reference to Fig. 1. Particular preferred embodiments are then described in more detailed with reference to Figs. 2-5. Generally, the

equipment of this invention is designed and sized both for high volume manufacturing of epitaxial GaN layers on substrates and also for economy of construction and operation.

GENERAL EMBODIMENTS OF THE INVENTION

5 For convenience and without limitation, the invention is generally described with reference to Fig. 1 in terms of three basic subsystems: subsystems 1 for providing process gases (or liquids); subsystems 3 including a reaction chamber; and subsystems 5 for waste abatement.

As noted above, HVM is an attribute of a combination of various physical features of
10 the system including the generic features described herein:

1. EXTERNAL SOURCE OF GaCl_3

The structure of the first subsystem, the process gas subsystem, especially the gallium compound vapor source, is an important feature of the invention. Known GaN VPE processes
15 are now briefly described. GaN VPE epitaxy comprises synthesizing GaN directly on the surface of a heated substrate from precursor gases containing nitrogen (N) and gallium (Ga) (and, optionally, one or more other Group III metal containing gases in order to form mixed nitrides and optionally, one or more dopants to provide specific electronic conductivity). The Ga-containing gas is usually gallium monochloride (GaCl) or gallium trichloride (GaCl_3), or a
20 gallium-organic compound, e.g., tri-ethyl-gallium (TEG) or tri-methyl-gallium (TMG). In the first case, the process is referred to as HVPE (Halide Vapor Pressure Epitaxy and in the second as MOVPE (Metal Organic Vapor Pressure Epitaxy).

The chemical properties of GaCl (stability only at high temperatures) require that GaCl vapor be synthesized in situ in the reaction vessel, e.g., by passing HCl over a boat containing
25 liquid Ga. In contrast, GaCl_3 is a stable solid at ambient conditions (in the absence of moisture) which is commonly supplied in sealed quartz ampoules each with about 100 g or so. TMG and TEG are volatile liquids. The N-containing gas is usually ammonia (NH_3), and semiconductor quality NH_3 is available in standard cylinders.

Alternately plasma-activated N_2 , e.g., containing N ions or radicals, can be used as the
30 N-containing gas. Molecular N_2 is substantially unreactive with GaCl_3 or GaCl even at high process temperatures. Nitrogen radicals can be prepared in a manner known in the art, in general, by providing energy to split a nitrogen molecule, for example, by adding a RF source to a nitrogen line to generate an electromagnetically induced plasma. When operating in this mode, the pressure in the reactor is usually reduced.

Of the known VPE processes, MOCVD and GaCl HVPE have been found to be less desirable for sustained, high Volume Manufacturing of Group III nitride layers. First, MOCVD is less desirable for the growth of films greater than 10 μ m because achievable deposition rates are less than 5% of the deposition rates achievable by HVPE processes.

5 For example, HVPE deposition rate can be in the range of 100- 1000 μ /hour or more, while MOCVD rates are typically less than 10 μ /hour. Second, GaCl HVPE is less desirable because this process requires that a supply of liquid Ga be present in the reaction chamber in order to form GaCl by reaction with HCl. It has been found that maintaining such a supply of liquid Ga in a form that remains reactive with HCl and that is sufficient for high volume
10 manufacturing is difficult.

Therefore, equipment of the invention is primarily directed to GaCl₃ HVPE for high volume manufacturing. Optionally, it can also provide for MOCVD for, e.g., deposition of buffer layers and the like. However, use of GaCl₃ HVPE for high volume manufacturing requires a source of GaCl₃ vapor that achieves a sufficient flow rate that can be maintained
15 without interruption (except for wafer loading/unloading in the reaction chamber) for a sufficient period. Preferably, an average sustained deposition rate is in the range of 100 to 1000 μ m/hour of GaN per hour so that approximately one wafer (or one batch of multiple wafers) requires no more than one or two hours of deposition time for even thick GaN layers. Achieving such a preferred deposition rate requires that the source provide a mass flow of
20 GaCl₃ vapor at about approximately 250 or 300 g/hour (a 200 mm circular 300 μ m thick layer of GaN comprises about approximately 56 g of Ga while GaCl₃ is about 40% Ga by weight). Further, such a flow rate can preferably be maintained for a sufficient duration so that production interruptions required to recharge/service the source are limited to at most one per week, or more preferably one at least every two to four weeks. Accordingly, it is preferred
25 that the flow rate can be maintained for at least 50 wafers (or batches of multiple wafers), and preferably for at least 100, or 150, or 200, or 250 to 300 wafers or batches or more. Such a source is not known in the prior art.

The equipment of the invention provides a GaCl₃ source that overcomes problems in order to achieve preferred flow rates and durations. Achieving preferred flow rates has been
30 hindered in the past by certain physical properties of GaCl₃. First, at ambient conditions, GaCl₃ is a solid, and vapor can be formed only by sublimation. However, it has been determined that GaCl₃ sublimation rates are inadequate for providing vapor at preferred mass flow rates. Second, GaCl₃ melts at about 78°C, and vapor can then be formed by evaporation

from the liquid surface. However, it has also been determined that evaporation rates are inadequate for providing preferred mass flow rates. Further, typical physical means for increasing rate of evaporation, e.g., agitation, bubbling, and the like, do not increase evaporation rate sufficiently because GaCl₃ liquid is known to be relatively viscous.

5 What is needed is a form of liquid GaCl₃ of sufficiently lower viscosity, and it has been observed and discovered that beginning at about approximately 120°C, and especially at about approximately 130°C or above, GaCl₃ assumes such a lower viscosity state with a viscosity similar to, e.g., that of water. And further, it has been observed and discovered that in this lower viscosity state, routine physical means are capable of effectively raising the
10 GaCl₃ evaporation rate sufficiently to provide the preferred mass flow rates.

 Accordingly, the GaCl₃ source of this invention maintains a reservoir of liquid GaCl₃ with temperature T1 controlled to about approximately 130°C and provides physical means for enhancing the evaporation rate. Such physical means can include: agitate the liquid; spray the liquid; flow carrier gas rapidly over the liquid; bubble carrier gas through the liquid;
15 ultrasonically disperse the liquid; and the like. In particular, it has been discovered that bubbling an inert carrier gas, such as He, N₂ or H₂ or Ar, by arrangements known in the art through a lower viscosity state of liquid GaCl₃, e.g., GaCl₃ at about 130°C, is capable of providing the preferred mass flow rates of GaCl₃. Preferred configurations of the GaCl₃ source have increased total surface area in proportion to their volume in order to achieve
20 better temperature control using heating elements outside of the reservoir. For example, the illustrated GaCl₃ source is cylindrical with a height that is considerably greater than the diameter. For GaCl₃, this would be around 120 g per hour for a period of at least 48 hours, to 250 g per hour for a period of at least 100 hours, to 500 g per hour for a period of at least one week, to as high as 750 to 1000 g per hour for a period of at least a month.

25 Moreover, a GaCl₃ source capable of the preferred flow rate and duration cannot rely on GaCl₃ supplied in individual 100 g ampoules. Such an amount would be sufficient for only 15 to 45 minutes of uninterrupted deposition. Therefore, a further aspect of the GaCl₃ source of this invention is large GaCl₃ capacity. To achieve the high-throughput goals of this invention, the time spent recharging GaCl₃ source is preferably limited. However, recharging
30 is made more complicated by the tendency of GaCl₃ to react readily with atmospheric moisture. The GaCl₃ charge, the source, and the GaCl₃ supply lines must be free of moisture prior to wafer production. Depending on the throughput goals of various embodiments, the invention includes sources capable of holding at least about 25 kg of GaCl₃, or at least about

35 kg, or at least about 50 to 70 kg (with an upper limit determined by requirements of size and weight in view of the advantages of positioning the source in close proximity to the reaction chamber). In a preferred embodiment, the GaCl_3 source can hold between about 50 and 100 kg of GaCl_3 , preferably between about 60 and 70 kg. It will be realized that there is
5 no real upper limit to the capacity of the GaCl_3 source other than the logistics of its construction and use. Furthermore, multiple sources of GaCl_3 could be set up through a manifold to permit switching from one source to another with no reactor downtime. The empty source could then be removed while the reactor is operating and replaced with a new full source.

10 A further aspect of the GaCl_3 source of this invention is careful temperature control of the supply lines between the source and the reaction chamber. The temperature of the GaCl_3 supply lines and associated mass flow sensors, controllers, and the like preferably increase gradually from T2 at the exit from the source up to T3 at reaction chamber inlet 33 in order to prevent condensation of the GaCl_3 vapor in the supply lines and the like. However,
15 temperatures at the reaction chamber entry must not be so high that they might damage sealing materials (and other materials) used in the supply lines and chamber inlet, e.g., to seal to the quartz reaction chamber, for gaskets, o-rings, and the like. Currently, sealing materials resistant to Cl exposure and available for routine commercial use in the semiconductor industry generally cannot withstand temperatures greater than about 160°C. Therefore, the
20 invention includes sensing the temperature of the GaCl_3 supply lines and then heating or cooling the lines as necessary (generally, "controlling" the supply line temperatures) so that the supply line temperatures increase (or at least do not decrease) along the supply line from the source, which is preferably at about approximately 130°C, up to a maximum at the reaction chamber inlet, which is preferably about approximately 145 to 155°C (or other
25 temperature that is safely below the high temperature tolerance of o-rings or other sealing materials). To better realize the necessary temperature control, the length of the supply line between the source apparatus and the reaction chamber inlet should be short, preferably less than about approximately 1 ft., or 2 ft. or 3 ft. The pressure over the GaCl_3 source is controlled by a pressure control system 17.

30 A further aspect of the GaCl_3 source of this invention is precise control of the GaCl_3 flux into the chamber. In a bubbler embodiment, the GaCl_3 flux from the source is dependent on the temperature of the GaCl_3 , the pressure over the GaCl_3 and the flow of gas that is bubbled through the GaCl_3 . While the mass flux of GaCl_3 can in principle be controlled by

any of these parameters, a preferred embodiment is to control the mass flux by varying the flow of a carrier gas by controller 21. Routinely-available gas composition sensors such as a Piezocor, and the like 71 can be used to provide additional control of the actual GaCl₃ mass flux, e.g., in grams per second, into the reaction chamber. In addition, the pressure over the GaCl₃ source can be controlled by a pressure control system 17 placed on the outlet of the bubbler. The pressure control system, e.g. a back pressure regulator, allows for control of the over pressure in the source container. Control of the container pressure in conjunction with the controlled temperature of the bubbler and the flow rate of the carrier gas facilitates an improved determination of precursor flow rate. Optionally, the container also includes an insulating outer portion.

It is desirable that the materials used in the GaCl₃ source, in the GaCl₃ supply lines, and in the inlet manifold structures in contact with GaCl₃ are chlorine resistant. For metal components, a nickel-based alloy such as Hastelloy, or tantalum or a tantalum-based alloy is preferred. Further corrosion resistance for metal components can be provided through a protective corrosion resistant coating. Such coatings can comprise silicon carbide, boron nitride, boron carbide, aluminum nitride and in a preferred embodiment the metal components can be coated with a fused silica layer or a bonded amorphous silicon layer, for example SILTEK® and SILCOSTEEL® (commercially available from Restek Corporation) has been demonstrated to provide increased corrosion resistance against oxidizing environments. For non-metal components, chlorine resistant polymeric materials (either carbon or silicone polymers) are preferred.

In view of the above, a preferred GaCl₃ source capable of holding preferred amounts of GaCl₃ is referred to herein as acting "continuously" in that, in an appropriate embodiment, the source can deliver its contained GaCl₃ without interruption to deliver the desired amounts for the recited time durations. It should be understood, however, that, in a particular embodiment, the reaction chamber (or other component of the present system) is or can be so constructed or certain process details are performed, so that intermittent chamber maintenance, e.g., cleaning and so forth, is required. In contrast, the GaCl₃ source is configured and dimensioned to provide the desired amounts of the precursor in an uninterrupted manner to facilitate high volume manufacture of the Group III-V product. Thus, the source is capable of providing these amounts without having to be shut down or otherwise discontinued for replenishment of the solid precursor.

This can be achieved either by providing sufficiently large quantities of the solid precursor in a single reservoir, or by providing multiple reservoirs that are manifolded together. Of course, a skilled artisan would understand that in a manifolded system, one reservoir can be operated to provide the gaseous precursor while one or more other reservoirs are being replenished with solid precursor material, and that this remains an uninterrupted system since it has no affect on the operation of the reactor. In such embodiments, the GaCl₃ source is also referred to herein as acting continuously in that the source can deliver its contained GaCl₃ without refilling, opening, cleaning, replenishing or other procedure during which the source is not fully functional. In other words, the source does not by itself necessitate interruption of GaN deposition.

Also, as described, a preferred GaCl₃ source can contain GaCl₃ in a single reservoir. Also, a preferred source can include multiple reservoirs (i.e., 2, 5, 10 etc.) having outlets which are manifolded so that GaCl₃ vapor can be delivered from the multiple reservoirs in sequence or in parallel. In the following, both embodiments are often referred to as a single source. In preferred embodiments, the equipment of this invention can also provide for sources for Group III metal organic compounds so that MOCVD processes can be performed. For example, MOCVD can be used to, e.g., deposit thin GaN or AlN buffer layers, thin intermediate layers, layers of mixed metal nitrides, and so forth. Additional process gases can be routinely supplied as known in the art.

The group V precursor is a gas containing one or more Group V atoms. Examples of such gases include NH₃, AsH₃ and PH₃. For the growth of GaN, NH₃ is typically used because it can provide sufficient incorporation of N at typical growth temperatures. Ammonia and other N precursors are external sources. For example, semiconductor grade NH₃ is readily available in cylinders 19 of various sizes, and carrier gases 72 are available as cryogenic liquids or as gases, also in containers of various sizes. Fluxes of these gases can be routinely controlled by mass flow controllers 21 and the like. In alternative embodiments, the equipment of this invention can also provide for sources of other Group III chlorides.

2. REACTOR GEOMETRY

Next, to achieve increased economy, the reactor subsystems are preferably adaptations of commercially available reactor systems. Available reactors preferred for adaptation and use in this invention include as-is most or all of the features to be next described. These features have been determined to be useful for HVM of GaN layers with the modifications and enhancements disclosed herein. Although the following description is directed mainly to

embodiments that adapt existing equipment, reactors and reactor systems can be purpose built to include the to-be-described features. The invention includes both redesigning and modifying existing equipment and designing and fabricating new equipment. The invention also includes the resulting equipment.

5 Generally, preferred reaction chambers have horizontal process-gas flow and are shaped in an approximately box-like or hemi-sphere like configuration with lesser vertical dimensions and greater horizontal dimensions. Certain features of horizontal reaction chambers are important in limiting unproductive reactor time and achieving HVM of quality GaN wafers.

10 3. LOW THERMAL MASS SUSCEPTOR AND LAMP HEATING

First, time spent ramping-up temperature after introducing new wafers and time spent ramping-down temperature after a deposition run is not productive and should be limited or minimized. Therefore, preferred reactors and heating equipment also have lower thermal masses (i.e., ability to absorb heat quickly), and the lower the thermal masses the more preferred. A preferred such reactor is heated with infrared (IR) heating lamps and has IR transparent walls Fig. 1 illustrates reactor 25 made of quartz and heated by lower longitudinal IR lamps 27 and upper transverse IR lamps 29. Quartz is a preferred chamber wall material, since it is sufficiently IR transparent, sufficiently Cl resistant, and sufficiently refractory.

20 4. CLOSED LOOP TEMPERATURE CONTROL ON CHAMBER WALLS AND FLANGES

Time spent cleaning reaction chamber interiors is also not productive and also should be limited or minimized. During GaN deposition processes, precursors, products, or byproducts can deposit or condense on interior walls. Such deposition or condensation can be significantly limited or abated by controlling the temperature of the chamber walls generally by cooling them to an intermediate temperature that is sufficiently high to prevent condensation of precursors and byproducts, but that is sufficiently low to prevent GaN formation and deposition on the walls. Precursors used in GaCl_3 HVPE processes condense at below about 70 to 80°C; the principal byproduct, NH_4Cl , condenses only below about 140°C; and GaN begins to form and deposit at temperatures exceeding about 500 °C. Chamber walls are controlled to temperature T5 that is preferably between 200°C, which has been found to be sufficiently high to significantly limit precursor and byproduct condensation, and 500°C, which has been found to be sufficiently low to significantly limit GaN deposition on chamber walls. A preferred temperature range for the chamber walls is 250 to 350°C.

Temperature control to preferred ranges generally requires cooling chamber walls. Although IR transparent, chamber walls are nevertheless heated to some degree by heat transferred from the high temperature susceptor. Fig. 1 illustrates a preferred cooling arrangement in which reaction chamber 25 is housed in a full or partial shroud 37 and cooling air is directed through the shroud and over and around the exterior of the reaction chamber. Wall temperatures can be measured by infrared pyrometry and cooling air flow can be adjusted accordingly. For example, a multi-speed or a variable speed fan (or fans) can be provided and controlled by sensors sensitive to chamber wall temperatures.

5. LOAD LOCK, CASSETTE TO CASSETTE

Wafer loading and unloading time is also not productive. This time can be routinely limited by automatic equipment schematically illustrated at 39. As it known in the art, this equipment can store wafers, load wafers into, and unload wafers from the reaction chamber, and generally comprises, e.g., robotic arms and the like that move wafers, e.g., using transfer wands, between external holders and the susceptor in the reaction chamber. During wafer transfer, the reaction chamber can be isolated from ambient exposure by intermediate wafer transfer chambers. For example, controllable doors between the transfer chamber and the exterior can permit loading and unloading and can then seal the transfer chamber for ambient exposure. After flushing and preparation, further controllable doors between the transfer chamber and the reactor can open to permit placement and removal of wafers on the susceptor. Such a system also prevents exposure of the reactor interior to oxygen, moisture or other atmospheric contaminants and reduces purging times prior to load and unload of wafers. It is preferred to use a quartz Bernoulli transfer wand because it reduces unproductive time by allowing handling of hot wafers without causing contamination.

6. SEPARATE INJECTION

Process gas flow control, from inlet manifold 33 in the direction of arrow 31 to outlet manifold 35, is important for depositing high quality GaN layers. This flow includes the following preferred characteristics for the process gases. First, the gallium containing gas, e.g., GaCl₃, and the nitrogen containing gas, e.g., NH₃, preferably enter the reaction chamber through separate inlets. They should not be mixed outside the reaction chamber because such mixing can lead to undesirable reactions, e.g., forming complexes of GaCl₃ and NH₃ molecules, that interfere with subsequent GaN deposition.

Then, after separate entry, the GaCl_3 and NH_3 flows are preferably arranged so that the gas has a uniform composition in space and time over the susceptor. It has been found that the III/V ratio should vary over the face of the susceptor (and supported wafer or wafers) at any particular time preferably by less than approximately 5%, or more preferably by less than approximately 3% or 2% or 1%. Also, the III/V ratio should be similarly substantially uniform in time over all portions of the face of the susceptor. Accordingly, the GaCl_3 and NH_3 velocity profiles should provide that both gases both spread laterally across the width of the reaction chamber so that upon arriving at the susceptor both gases have a non-turbulent flow that is uniform across the width of the reaction chamber and preferably at least across the diameter of the susceptor.

Finally, the flow should not have recirculation zones or regions of anomalously low flow rates, where one or more of the process gases can accumulate with an anomalously high concentration. Localized regions of low gas flow, or even of gas stagnation, are best avoided.

Preferred process gas flow is achieved by careful design or redesign of the inlet manifold of a new or existing reaction chamber. As used here the term "inlet manifold" refers to the structures that admit process and carrier gases into a reaction chamber whether these structures are unitary or whether they comprise two or more physically separate units.

Inlet manifold designed and fabricated to have the following general features have been found to achieve preferred process gas flows. However, for most embodiments, it is advantageous for the gas flow into a selected reaction chamber produced by a proposed inlet manifold design to be modeled using fluid dynamic modeling software packages known in the art. The proposed design can thereby be iteratively improved to achieve increased uniformity prior to actual fabrication.

First, it has been found advantageous that process gas entry into the reaction chamber be distributed across some, most or all of the width of the chamber. For example, multiple gas inlet ports or one or more slots through which gas can enter can be distributed laterally across the width of the chamber. A carrier gas such as nitrogen or hydrogen can be introduced to assist in directing the GaCl_3 and the NH_3 gases through the reactor to the desired reaction location above the susceptor. Further, to prevent spurious deposition in the vicinity of the inlet ports, it is advantageous for the actual inlet ports to be spaced with respect to the heated susceptor so that they are not heated above approximately 400-500°C. Alternately, the inlet ports can be cooled or can be spaced apart so the process gases do not mix in their vicinity.

Next it has been found that gas flow properties produced by a particular configuration of the GaCl_3 and NH_3 inlets can be improved, or "tuned" dynamically. Secondary purge gas flows impinging on or originating for example from under the susceptor and mixing with the primary GaCl_3 , and NH_3 flows can be used to alter these flows to increase uniformity of composition and velocity or prevent deposition on reactor components. For example, in embodiments where the GaCl_3 and NH_3 flows enter the reaction chamber from different inlets, it has been found advantageous to provide a purge gas flow entering into the reaction chamber somewhat upstream of GaCl_3 , and NH_3 flows to confine the process gases above the intended deposition zone and to shield the side walls of the reactor from unintended deposition. For these purposes, it is advantageous to introduce a greater amount of carrier gas laterally near the chamber walls and a lesser amount centrally about the middle of the chamber.

Also, preferred inlet manifolds provide for dynamic adjustment of, at least, one of the process gas flows so that non-uniformities observed during operation can be ameliorated. For example, inlets for a process gas can be divided into two or more streams and individual flow control valves can be provided to independently adjust the flow of each stream. In a preferred embodiment, GaCl_3 inlets are arranged into five streams with independently controllable relative flow.

Further aspects of a preferred inlet manifold include temperature control. Thereby, inlet manifold temperatures T3 can be controlled both to prevent the condensation of precursors, e.g., GaCl_3 , and to prevent damage to temperature-sensitive materials, e.g., gasket or O-ring materials. As discussed, the GaCl_3 inlet ports should be at a temperature no less than the highest temperatures reached in the GaCl_3 supply line, which is preferably increased from about approximately 110°C to about approximately 150°C. Commercially available chlorine-resistant, sealing materials, such as gasket materials and O-ring materials, available for use in the inlet manifold, in particular for sealing the manifold to the quartz reaction chamber, begin to deteriorate at temperatures in excess of about approximately 160°C. Chlorine-resistant sealing materials such as silicone o-rings usable to higher temperatures, if available, can also be used, in which case the inlet manifold upper temperature limit can be raised.

Accordingly, inlet manifold temperature T3 should be controlled to remain in the range of about approximately 155 to 170°C by either supplying heat to raise the temperature from ambient or removing transferred heat from the hot reaction chamber and very hot susceptor. In preferred embodiments, an inlet manifold includes temperature sensors and

channels for temperature control fluids. For example, temperatures of 155 to 170°C can be achieved by circulating a temperature-controlled GALDEN™ fluid. Other known fluids can be used for other temperature ranges. The fluid channels preferably run in proximity to the temperature sensitive portions of the inlet manifold, e.g., the GaCl₃ inlet ports and sealing o-rings. Channel arrangement can be chosen more precisely in view of thermal modeling using software packages known in the art.

GaCl₃ molecules whether in the solid or liquid or vapor phase are known to exist mainly in the Ga₂Cl₆ dimer form. That form is actually very stable up to 800°C, Thermodynamic calculations corroborated by gas phase Raman spectroscopy have confirmed that at 300°C more than 90% of the gas phase is composed of the dimer molecule and at 700°C more than 99% of the dimer has decomposed into the GaCl₃ monomer.

As the dimer molecule is injected through a metallic injection port kept at temperatures at or below 150°C, the decomposition of the dimer will occur only in contact with the hot susceptor which is at temperature above 1000°C. Depending on the velocity of the gas above the susceptor or its residence time the portion of the dimer that will be decomposed might be too small to sustain a high growth rate on the wafer. The GaN deposition process proceeds through the adsorption of GaCl₃ and its further decomposition to GaCl_x with $x < 3$ until all chlorine has been removed to obtain an adsorbed atom of Ga. It is therefore desired to operate from the monomer form of GaCl₃. A preferred embodiment of the invention introduces the dimer through a quartz tube under the reactor chamber situated upstream of the susceptor region. This quartz tube connects to the reactor chamber through a funnel with an oval cross-section. Energy is provided to the dimer while in the funnel to decompose the dimer to the monomer. A preferred embodiment uses IR radiation from IR lamps located and shaped in such a way that the quartz tube and funnel receive a high flux of IR radiation. In this embodiment, the funnel region is filled with IR absorbent materials and the radiation power adjusted to bring the IR absorbent material to a temperature of 600°C or more preferably 700°C or higher. As the dimer form of GaCl₃ is injected in the quartz injector and passes through the hot funnel zone, the dimer will be decomposed to the monomer and be injected in the reaction chamber just upstream of the susceptor. Preferably the region between the injection point of the GaCl₃ into the reactor and the susceptor is maintained at a temperature above 800°C to prevent the re-formation of the dimer. A preferred embodiment is to use a SiC plate between the funnel and the susceptor which is heated by the IR heating lamps to maintain a temperature above 700°C and preferably above 800°C.

7. SUSCEPTOR AND MULTI-WAFER SUSCEPTOR

The susceptor and its mounting can be of standard construction as generally known in the art. For example, it can comprise graphite coated with silicon carbide or silicon nitride, or alternatively, a refractory metal or alloy. The susceptor is preferably mounted for rotation on a shaft. During GaN deposition, susceptor temperatures T4 can be approximately 1000 to 1100°C (or higher) and are maintained by the quartz IR lamps controlled by known temperature control circuitry. To avoid forming a dead zone beneath the susceptor, the susceptor mounting preferably provides for injection of purge gas. This injection is also advantageous because it can limit or minimize unwanted deposition on the underside of the heated susceptor and of adjacent components that may also be heated (directly or indirectly). The susceptor can be configured to hold one or more substrates.

8. HEATED EXHAUST

Reaction chamber outlet manifold 35 provides for the free and unobstructed flow of exhaust gases from the reaction chamber through the exhaust lines 41 and to waste abatement system 5. The exhaust system can also include a pump (42) and associated pressure control system (pressure control valve (44), pressure gauge (46) and associated control equipment to permit operation at reduced pressure). The outlet manifold exhaust lines and pressure control equipment (if used) are advantageously also temperature controlled to limit condensation of reaction products. Exhaust gases and reaction products typically comprise the carrier gases; un-reacted process gases, GaCl₃ and NH₃; reaction byproducts which are primarily NH₄Cl, NH₄GaCl₄, HCl, and H₂. As described above, temperatures above about approximately 130°C are required to prevent condensation of GaCl₃. NH₄Cl condenses into a powdery material below about approximately 140°C, and the outlet manifold and exhaust system should be kept above this temperature. On the other hand, to prevent deterioration of sealing materials, the outlet manifold temperature should not exceed about approximately 170°C.

Accordingly, outlet manifold temperature T6 is preferably maintained in the range of about approximately 155 to 170°C by temperature control means similar to those used for inlet manifold temperature control (including optional thermal modeling). Maximum exhaust line temperature T7 is limited by the maximum allowable temperature for the seals, preferably in the range of about 155 to 170°C.

9. WASTE MANAGEMENT

Considering next waste abatement subsystems 5, a preferred abatement system can assist in economical operation of the invention by recovery of waste gallium compounds exhausted from the reaction chamber. A single embodiment of the invention can exhaust 30 kg, or 60 kg, or more during (assuming approximately 50% waste) during a month of sustained, high volume manufacturing. At current Ga prices, it is economical to recover this waste Ga and recycle it into GaCl_3 precursor, thereby achieving effectively approximately 90 to 100% Ga efficiency.

Fig. 1 also schematically illustrates a preferred embodiment of waste abatement subsystem 5 that provides for gallium recovery and that can be readily adapted from commercially available products. The stream exhausted from reaction chamber 25 passes through exhaust lines 41 temperature controlled at T_7 to limit condensation of exhaust products, e.g., in the range of about 155 to 170°C or greater as convenient, and then into burner unit 43. The burner unit oxidizes the exhaust gases by passing it through high temperature combustion zone 45 comprising, e.g., H_2/O_2 combustion. The oxidized exhaust stream then passes through tube 47 into countercurrent water scrubber unit 49 where it moves in a countercurrent fashion with respect to water stream 51. The water stream removes substantially all water soluble and particulate components from the oxidized exhaust stream. The scrubbed exhaust gas is then released from the system 57.

The water stream with the soluble and particulate materials passes to separator 59 where particulate components, primarily particulate gallium oxides (e.g., Ga_2O_3), are separated 61 from the water soluble components, primarily dissolved NH_4Cl and HCl . Separation can be obtained by known techniques, such as screening, filtering, centrifugation, flocculation, and so forth. A single embodiment of the invention can produce 60kg, or up to 120kg, or more, of particulate Ga_2O_3 during each month of operation. The particulate gallium oxides gallates are collected and the Ga is advantageously recovered and recycled into, e.g., GaCl_3 by known chemical techniques: see, e.g., Barman, 2003, Gallium Trichloride, SYNLETT 2003, no. 15, p. 2440-2441. The water-soluble components are passed from the system.

10. GATE VALVE

A gate valve seals the reactor chamber interior from the exterior, which is often the interior of a transfer chamber. The gate valve and reactor chamber loading port, are preferably sized and configured so that when the gate valve is open, an automated wafer-

transfer device can freely transfer wafers between the reactor chamber and the transfer chamber. When closed, the gate valve in cooperation with an opposed face of the reactor chamber seal the interior of the reactor chamber. In the following, gate valves of this invention are generally described followed by more detailed description in view of Figs. 7A-B and 8A-C. Arrangement of a gate valve of this invention in a reactor system of this invention is in a subsequent section in view of Figs. 4 and 6.

Gate valves of this invention preferably include one or more gas ports and one or more temperature control mechanisms. Also, gate valves, or the opposed face of a reactor assembly, or both, include sealing materials arranged to actually accomplish and complete a tight seal between the reactor chamber interior and exterior.

Concerning gas ports, one or more gas ports are preferably provided and arranged to admit one or more species of selected gases (usually, one species) into a sealed reactor chamber, that is the gas ports are arranged across the face of the gate valve exposed to the reactor interior (equivalently, the exposed face). The arrangement can comprise patterns that place gas ports uniformly or non-uniformly across the exposed face. For example, in a non-uniform arrangement, the ports can be concentration towards the center of the exposed face, or concentrated towards one or both lateral sides of the exposed face, or in other non-uniform arrangements. Patterns of ports can comprise square lattices, rectangular lattices, hexagonal lattices, single rows, multiple rows, and the like.

In preferred embodiments, the ports are arranged in one or more parallel rows (equivalently, in a square or rectangular pattern) extending across the exposed face of the gate valve. They can be uniformly distributed across the exposed face or concentrated at the lateral sides of the exposed face. A gas (preferably one or more relatively inert gases) can be admitted through the ports in order to reduce unwanted deposits on the side walls of the reactor chamber, to reduce gas recirculation within the reactor chamber, and to reduce residence times of precursor and product gases in the reactor chamber. In addition, gas admitted through the ports can act to limit contact (and protect) between the exposed face of the gate valve and the process gases within the reactor chamber (i.e., the gas acts as a shield of the exposed face).

Concerning temperature control mechanisms, temperature control of the gate valve is an advantage of the present invention for the following reasons. First, the portion of the gate valve exposed to the reactor chamber (equivalently, exposed face) is preferably maintained at a high enough temperature so that gases in the reactor do not condense on the exposed face

and so that unwanted reactions or complex formation are not induced in the gases in the reactor by contact with the exposed face. Second, the portions of the gate valve that physically oppose and form a seal with corresponding portions of the entrance assembly of the reactor (equivalently, the sealing portion of the gate valve and the sealing portions of the reactor assembly) are preferably maintained at a low enough temperature so that thermal damage to auxiliary components of the unit, e.g., o-rings, seals, gaskets, etc, is limited or prevented. Also, the temperature of the exposed face should remain below the deposition/reaction temperatures, but this is virtually always the case.

High and low temperature thresholds depend on the particular process being conducted in a reactor chamber. In the case of HVPE growth of GaN, significant temperature thresholds include: the condensation temperature of reaction precursor GaCl_3 at or below $\approx 80^\circ\text{C}$ into a liquid form; the condensation temperature of reaction product NH_4Cl at or below $\approx 140 - 150^\circ\text{C}$ into a solid form (i.e., the reverse of sublimation); and the safe operating temperatures of currently-available, chlorine-resistant sealing materials at or below $\approx 150 - 160^\circ\text{C}$ (here, " $\approx$ " is a common mathematical symbol used herein with its common meaning of about or approximately).

Preferred gate valve assemblies (e.g., a combination of a gate valve and temperature control mechanisms) comprise both mechanisms capable of raising the temperature of an exposed face of the gate valve and lowering the temperature of a sealing portion. Further embodiments, however, can comprise only a temperature raising mechanism, or a temperature lowering mechanism, or neither. Further embodiments can comprise multiple mechanisms of either type. Also, temperature control mechanisms can be integral to the gate valve, or integral (or closely adjacent) to the sealing portion of the reactor, or external to but associated with the gate valve or the reactor, or a combination of such arrangements. In the following, preferred, but non-limiting, temperature control mechanisms are described. However, the invention can include temperature mechanism other than those described.

The exposed face of a gate valve can be heated by conduction from the body of the gate valve, which in turn can be heated by a number temperature control devices known to those with ordinary skill in the art, including but not limited to, resistance heating, induction heating, radiant heating, high temperature gas/liquid heating etc. In one preferred embodiment, the body (and thereby also the exposed face) of the gate valve can be heated and controlled by radiant heating elements (e.g., infrared elements) comprising either filament lamps or solid state devices or a combination thereof. The radiant heating elements are

preferably placed external to the reactor chamber (e.g., in the transfer chamber), because of the high temperatures and corrosive environment within the reactor chamber. The radiant IR heating elements can be arranged in the transfer chamber to be in close proximity to the gate valve for providing heating specifically directed to the unit so that the exposed face is at a high enough temperature to prevent condensation.

In an alternative preferred embodiment, the temperature of the exposed face of the gate valve assembly can be raised and controlled by the circulation of a heated fluid, e.g., a high temperature gas, through the body of the gate valve. The heated gas can be arranged to flow into passageways in the body of the gate valve, through the passageways, and then out for reuse or disposal. Further, heated gas in the passageways can be directed through some or all of the plurality of ports in the exposed face of the gate valve. Preferably, internal gas passageways are arranged to be near the exposed face so that the heated gas circulating through the body of the fixture imparts heating to the unit raising the temperature of the exposed face to a desired level to combat the build up of unwanted reactor deposits.

The sealing portion of the gate valve can be cooled directly or indirectly by, e.g., circulating cool fluids, including cool gases or cool liquids. In one preferred embodiment, cool fluids can be circulated in passageways within the sealing portion of the reactor and adjacent to the sealing materials or to the sealing portion of the gate valve. Alternatively, cool fluids can be circulated within the body of the gate valve in passageways in proximity to the sealing portion of the gate valve. In another preferred embodiment, cool gas can be circulated in passageways within the gate valve. Alternatively, cool gas flows can be directed towards the body of the gate valve from ports in the transfer chamber. The sealing portion of the gate valve is then cooled by conduction from the body exposed in the transfer chamber. For example, ambient gas can be removed from the transfer chamber, cooled, and then reintroduced into the transfer chamber and directed towards the gate valve.

In various embodiments, a gate valve assembly can include only one or more temperature control devices for raising the temperature of the exposed face, or only one or more temperature control devices for lowering the temperature of the sealing face, or one or more of both types of temperature control devices. An advantageous combination includes a temperature control device for raising the temperature of the exposed face together with a temperature control device for lowering the temperature of the sealing face. For example, the temperature of the exposed face can be raised by circulating high temperature gas through passageways in the gate valve body (and out of the gate valve ports into the reactor), and the

temperature of the sealing face can be lowered by circulating low temperature fluid (e.g., in the sealing portion of the reactor or gate valve). Another exemplary combination includes circulating a heated gas through passageways in the gate valve body but controlling the temperature of the heated gas so that the temperature of the exposed face is sufficiently high but the temperature of the sealing portion is not raised above its thermal damage threshold.

A gate valve assembly preferably includes one or more thermocouples to provide feedback by which the heating and/or cooling mechanisms can be adjusted to maintain the temperature of the exposed face of the gate valve sufficiently high and to maintain the temperature of the sealing portion sufficiently low. Thermocouples can be situated in and around the gate valve assembly in the transfer chamber and also in the reactor chamber.

Fig. 7A schematically illustrates an exemplary arrangement of a gate valve of this invention within a typical CVD system. This figure illustrates transfer chamber 703 adjacent to reactor chamber 713; rear faceplate assembly 725 of the reactor chamber bounding both the transfer chamber and the reactor chamber; and a loading port between the two chambers sized to permit material transfers. A gas, often a precursor gas, can be introduced into the reactor through port 715 which is illustrated as opening into the loading port between the chambers. As in the applications to be discussed with reference to Figs. 5 and 6, the reactor chamber often comprises quartz walls and is operated in a cold-wall manner.

The loading port between the chambers is sealed by gate valve 702. The gate valve is here illustrated in a closed position; its open position is indicated by dotted outline 705. Passage 719, a transfer opening, assumes position 719' when the gate valve is open, and in this position is aligned with the reactor loading port so that material can be transferred through this transfer opening and then through the loading port without hindrance. Thereby, the gate valve will not interfere with material transfer between the chambers. Many mechanisms can be employed to open and close the gate valve; illustrated here is a generic mechanism 704 which rotates the gate valve about pivot 711.

Preferably, as illustrated, the gate valve is also provided with internal passageways and a plurality of ports 707 through which gas can enter the reactor chamber.

Preferably, the seal formed by contact of the sealing portion of the gate valve with the sealing portion of the reactor chamber is completed and augmented by sealing materials formed as gaskets, O-rings, and the like, and arranged between the opposing sealing portions. Such sealing materials are generically illustrated as seals 717-1 and 717-2. In the case of HVPE manufacture of GaN, the sealing materials are preferably resistant both to chlorine

compounds and to temperatures up to a threshold $\approx 150 - 170^{\circ}\text{C}$ (or higher if such sealing materials become available).

Fig. 7B illustrates in cross-section gate valve 702. A gate valve pivot shaft can extend through opening 711. Transfer opening 709 provides for material transfer as described. The gate valve include internal plenum-like gas passageway 707 leading to a plurality of ports 707 in the face of the valve. Recesses 717-1 and 717-2 are for retaining an O-ring encircling the exposed face of the gate valve. An O-ring can also be held by faceplate assembly 725.

Fig. 7A also illustrates several gate-valve temperature control mechanisms. The gate valve, and thereby the exposed face of the gate valve, can be heated by exemplary heating lamp 701, e.g., an IR heating lamp. An absorptive coating can be placed on the rear portion of the gate valve. Alternatively, two or more heating lamps can be used which can be placed in different locations, or in multiple locations, around the gate valve. The exposed face of the gate valve can also be heated passing hot gas through gas passageways 707 interior to the valve body. Preferably some or all of the heated gas passes into the reactor chamber through ports 707 in the exposed face.

Sealing materials 717-1 and 717-2 are arranged between the sealing portions of gate valve 702 and the sealing portions of reactor faceplate assembly 725. These materials can be cooled by circulating cooling fluids either within the gate valve or within the faceplate assembly (or within both). Here, cooling fluid passageways 721-1 and 721-2 are illustrated in the faceplate assembly adjacent to sealing materials 717-1 and 717-2. These cooling mechanisms preferably cool primarily regions of the gate valve and faceplate in the vicinity of the sealing materials. Cooling mechanisms are preferably omitted if sealing materials can resist expected temperatures, or are not needed at all.

For completeness, also illustrated are seals between reactor chamber 713 and faceplate assembly 725 which are also completed and augmented by sealing materials 719-1 and 719-2. These latter sealing materials can be protected, if necessary, from high reactor temperatures by circulating cooling fluid in passageways 723-1 and 723-2.

Thermocouples (not illustrated) can be arranged in and around the gate valve and adjacent portions of the reactor assembly to provide feedback by which the heating and/or cooling devices can be adjusted. Preferably, such temperature feedback reflects the temperature of the exposed face so that this temperature can be maintained sufficiently high, and also reflects the temperature of the sealing materials so that this temperature can be maintained sufficiently low.

This invention includes embodiments of gate valves having a plurality of discharge ports in the exposed face for discharging gas, one or more inlet ports for receiving gas, especially heated gas, and internal passageways connecting inlet and discharge ports. Figs. 8A-C illustrate three gate valve embodiment, each having different number and arrangement of these ports. The three illustrated embodiments are not limiting; the invention includes other numbers and arrangements. Common elements of all three illustrated gate valves include: pivot openings and shafts 828, transfer openings 821-1, 825-2, and 825-3, and O-ring seals 829-1, 829-2, and 829-3.

First concerning discharge ports, Fig. 8A illustrates a gate valve with a single row of discharge ports 821-1 arranged with greater numbers towards both lateral peripheries of exposed face gate valve and with lesser numbers in the vicinity of the center of the exposed face. Fig. 8B illustrates a gate valve with a regular, rectangular arrangement of discharge ports aligned in three, parallel row and occurring in constant numbers across the entire exposed face. Fig. 8C illustrates a variation of the arrangement of Fig. 8B in which extra discharge ports are arranged in the regions at the lateral edge of the exposed face that were occurring by inlet ports in Fig. 8B.

Concerning inlet ports, gate valve construction is simplified if gas can be circulated into passageways within the gate valve from passageways in the faceplate assembly of the reactor chamber. When the gate valve is closed, the openings of one or more passageways in the faceplate assembly can become aligned with the openings of one or more corresponding passageways in the gate valve. The junction between these passageways can be sealed by O-rings and the like. Figs. 8A and 8C illustrate gate valves each with two such ports, 827-1 and 827-3, arranged at both lateral edges of the sealing portion of the gate valve and outside of O-rings 821-1 and 821-3. Being outside of these O-rings, any gas that escapes from between these passageway seals escapes into the transfer chamber. Fig. 8B illustrates a gate valve with two such ports, 827-2, arranged at both lateral edges of the sealing portion of the gate valve but inside of O-ring 821-2. Being inside of this O-ring, any gas that escapes from between the inlet passageway seals escapes into the reactor chamber.

A PREFERRED PARTICULAR EMBODIMENT OF THE INVENTION

Next described is a particular preferred embodiment of the invention that has been generally described above. This embodiment is based on the modification and adaptation of an EPSILON® series, single-wafer epitaxial reactor from ASM America, Inc. Accordingly many of the following features are specific to this preferred particular embodiment. However,

these features are not limiting. Other particular embodiments can be based on modification and adaptation of other available epitaxial reactors and are within the scope of the invention.

Figs. 2A-C illustrate aspects of GaCl₃ delivery system 101 including reservoir 103, which can hold 50 to 75 kg of GaCl₃ and can maintain it at as a liquid at a controlled
5 temperature of up to about approximately 130 to 150°C, and supply assembly with supply lines, valves and controls 105, which provide a controlled mass flow of GaCl₃ to the reactor chamber while limiting or preventing GaCl₃ condensation within the lines. The reservoir includes internal means for enhancing evaporation of the liquid GaCl₃. In a preferred
10 embodiment, these include a bubbler apparatus as known in the art; in alternative embodiments, these can include means for physical agitation of the GaCl₃ liquid, for spraying the liquid, for ultrasonic dispersal of the liquid, and so forth. Optionally, the supply line (or delivery line) includes a coaxial portion having an inner line conveying the carrier gas and the Group III precursor and an enclosing coaxial line providing an annular space inside the enclosing line but outside the inner line. The annular space can contain a heating medium.

15 Fig. 2C illustrates an exemplary arrangement of delivery system 101 in cabinet 135 which is positioned adjacent to conventional process gas control cabinet 137. To limit the length of the GaCl₃ supply line, cabinet 135 is also positioned adjacent to the reaction chamber, which here is hidden by cabinet 137. Process gas control cabinet 137 includes, for example, gas control panel 139 and separate portions 141 - 147 for additional process gases or
20 liquids, such as a Group III metal organic compounds.

Fig. 2B illustrates preferred supply assembly 105 in more detail. Valves 107 and 109 control lines that conduct carrier gas into reservoir 103, then through the internal bubbler in the reservoir, and then out from the reservoir along with evaporated GaCl₃ vapor. They can isolate the reservoir for maintenance and so forth. Valve 110 facilitates the purging of the
25 system above the outlet and inlet valves of the container system. In particular, since condensation can possibly occur in the pig-tail elements 111, 112, valve 110 is useful in order to purge these areas. Control of the container pressure in conjunction with the controlled temperature of the bubbler and the flow rate of the carrier gas facilitates improved determination of precursor flow rate. The addition of valve 110 allows the complete delivery
30 system to be purged with non-corrosive carrier gas when not in growth mode, thereby reducing exposure of the system to a corrosive environment and consequently improving equipment lifetime. The assembly also includes valves 111 - 121 for controlling various aspects of flow through the supply lines. It also includes pressure controller and transducer

129 to maintain a constant pressure over the GaCl₃ container. Also provided is a mass flow controller 131 to provide a precise flow of carrier gas to the GaCl₃ container. These act to provide a controlled and calibrated mass flow of GaCl₃ into the reaction chamber. It also includes pressure regulators 125 and 127. The supply line assembly, including the supply
5 lines, valves, and controllers, is enclosed in multiple aluminum heating blocks in clamshell form to enclose each component. The aluminum blocks also contain temperature sensors that control supply line component temperatures so that the temperature increases (or at least does not decrease) from the output of the reservoir up to the inlet of the reaction chamber. A gas heater is provided to heat the inlet gas to the GaCl₃ source, preferably to a temperature of at
10 least 110°C.

Optionally, a purifier capable of removing moisture from the carrier gas down to no more than 5 parts per billion is placed in a carrier gas inlet line, and further a carrier gas filter is downstream of the carrier gas purifier. The carrier gas can be optionally configured with sinusoidal bends, e.g., pigtail 112, for providing increased heat exchange surface proximate to
15 the carrier gas heater.

Figs. 3A and 3B illustrate top views of a preferred embodiment of the reaction chamber 201. This reaction chamber has quartz walls and is generally shaped as an elongated rectangular box structure with a greater width and lesser height. A number of quartz ridges 203 span transversely across the chamber walls and support the walls especially when the
20 chamber is operated under vacuum. The reaction chamber is enclosed in a shroud that directs cooling air in order that the chamber walls can be controlled to a temperature substantially lower than that of the susceptor. This shroud generally has a suitcase-like arrangement that can be opened, as it is in these figures, to expose the reaction chamber. Visible here are the longer sides 205 and the top 207 of the shroud. Susceptor 215 (not visible in this drawing) is
25 positioned within the reactor. The susceptor is heated by quartz lamps which are arranged into two arrays of parallel lamps. Upper lamp array 209 is visible in the top of the shroud; a lower array is hidden below the reaction chamber. Portions of the inlet manifold are visible.

Fig. 3C illustrates a longitudinal cross-section through particular preferred reaction chamber 301 but omitting for strengthening ribs 203. Illustrated here are top quartz wall 303,
30 bottom quartz wall 305 and one quartz side wall 307. Quartz flange 313 seals the inlet end of the reaction chamber to the inlet manifold structures, and quartz flange 309 seals the outlet end of the reaction chamber to the outlet manifold structures. Port 315 provides for entry of process gases, carrier gases, and so forth, and port 311 provides for exit of exhaust gases.

The susceptor is generally positioned in semi-circular opening 319 so that its top surface is coplanar with the top of quartz shelf 317. Thereby a substantially smooth surface is presented to process gases entering from the inlet manifold structures so that these gases can pass across the top of the susceptor without becoming turbulent or being diverted under the susceptor.

- 5 Cylindrical quartz tube 321 provides for a susceptor support shaft on which the susceptor can rotate. Advantageously, carrier gas can be injected through this tube to purge the volume under the susceptor to prevent dead zones where process gases can accumulate. In particular, build up of GaCl_3 under the heated susceptor is limited.

10 The inlet manifold structures provide process gases through both port 315 and slit-like port 329. Gases reach port 329 first through quartz tube 323; this tube opens into flattened funnel 325 which allows gases to spread transversely (transverse to process gas flow in the reaction chamber); this funnel opens into the base of the reaction chamber through a transversely-arranged slot in shelf 317.

With reference to Fig. 6, the funnel is compactly filled with beads of silicon carbide 15 607 and a silicon carbide insert 327 in the top of the flattened funnel provides slit-like port 329 for entry of GaCl_3 from funnel 325 into the reaction chamber. Two IR spot lamps 601 and their reflector optics are located on each side of the funnel. A quartz sheath 603 containing a thermocouple 605 is inserted through the bottom of the quartz tube 323 up to about the middle of the funnel height in the middle of the SiC beads in order to enable close loop control of the 20 spot lamp power to maintain the SiC beads at a temperature of about 800°C . Preferably, GaCl_3 is introduced through port 329 and NH_3 is introduced through port 315. Alternatively, GaCl_3 can be introduced through port 315 and NH_3 can be introduced through port 329. Alternatively, an RF field may be created as known in the art in a lower portion of tube 323 so that the NH_3 can be activated by the creation of ions or radicals. Alternatively, some or all of 25 the NH_3 can be replaced by N_2 which will be similarly activated by the RF field. A SiC extension plate 335 is disposed between the slit port 329 and the edge of the susceptor. This SiC extension plate is heated by the main heating lamps to ensure that the dimer does not reform in the gas phase between the slit-like port 329 and the susceptor. The temperature of the SiC extension plate should be above 700°C and preferably above 800°C .

30 Fig. 4 illustrates a diagonally cut-away view of a particular preferred reaction/transfer chamber assembly comprising wafer transfer chamber 401 assembly mated to reaction chamber assembly 403. Structures which have been previously identified in Figs. 2 and 3 are identified in this figure with the same reference numbers. Exemplary transfer chamber 401

houses a robot arm, Bernoulli wand, and other means (not illustrated) for transferring substrates from the outside of the system into the reaction chamber and from the reaction chamber back to the outside. Transfer chambers of other designs can be used in this invention.

5 The reaction chamber assembly includes reaction chamber 301 mounted within shroud 405. Illustrated here are portions of bottom wall 407 and far wall 205 of the shroud. The shroud serves to conduct cooling air over the reaction chamber to maintain a controlled wall temperature. Certain reaction chamber structures have already been described including: bottom wall 305, side wall 307, flange 309 to outlet manifold, shelf 317, susceptor 215, and
10 cylindrical tube 321 for susceptor support and optional purge gas flow. The susceptor rotates in a circular opening 319 in rounded plate 409 which provides lateral stability to the susceptor and is coplanar with shelf 317, SiC extension plate 335 and slit-like port 329. The planarity of these components ensures a smooth gas flow from the gas inlet to the susceptor. Outlet manifold structures include plenum 407 which conducts exhaust gases from the reaction
15 chamber in the indicated directions and into exhaust line 419. The outlet manifold and flange 309 on the reaction chamber are sealed together with, e.g., a gasket or O-ring (not illustrated) made from temperature and chlorine resistant materials.

 Inlet manifold structures (as this term is used herein) are illustrated within dashed box 411. Plenum 211, described below, is sealed to the front flange of the reaction chamber with a
20 gasket or O-ring (not illustrated in Fig. 4, but O-ring 503 in Fig. 5) or the like made from temperature and chlorine resistant materials. gate valve 413 between the transfer chamber and the reaction chamber rotates clockwise (downward) to open a passage between the two chambers, and counterclockwise (upward) to close and seal the passage between the two chambers. The gate valve can be sealed against face plate 415 by means of, e.g., a gasket or
25 O-ring. The preferred material for the O-ring is the same as that mentioned above for other o-rings. The gate valve preferably also provides ports for gas entry as described below. Preferably, this gate valve is an embodiment of the above-described gate valve of this invention. The structure of the lower gas inlet, as previously described, includes communicating quartz tube 323, flattened funnel 325, and slit-like port 329.

30 Fig. 5 illustrates details of the particular preferred inlet manifold structures and their arrangement in the reaction chamber assembly. Structures which have been previously identified in Figs. 2 and 3 are identified in this figure with the same reference numbers. Considering first the surrounding reaction chamber assembly, reaction chamber assembly 403,

including shroud 405 and reaction chamber 301, is at the left, while transfer chamber structures 401 are at the right. Susceptor 215 and susceptor stabilizing plate 409 are inside the reaction chamber. Quartz flange 313 of the reaction chamber is urged against plenum structure 211 by extension 501 of shroud 405. The reaction chamber flange and plenum structure are sealed by O-ring gasket 503 which is visible in cross-section on both sides of port 315.

Considering now the inlet structure leading through slit-like port 329 for GaCl_3 (preferably, but optionally, NH_3 instead). It is comprised of a quartz tube 323, and funnel 325 that is longitudinally flattened but extended transversely so that it opens across a significant fraction of the bottom wall of the reaction chamber. Small beads or small tubes or any form of a porous IR absorbent material fill the funnel 325. Insert 327 fits into the upper opening of the funnel and includes slit-like port 329 that is angled towards the susceptor with an extension plate 335 that covers the space between the susceptor and the slit-like port. In operation, GaCl_3 (and optional carrier gases) moves upward in the supply tube, spreads transversely in the funnel, and is directed by the slit into the reaction chamber and towards the susceptor. Thereby, GaCl_3 moves from port 329 towards susceptor 215 in a laminar flow substantially uniform across the width of the reaction chamber.

Considering now inlet structures leading through port 315, these structures include plenum structure 211, face plate 415, and gate valve 413. NH_3 (preferably, but optionally, GaCl_3 instead) vapor is introduced into the plenum structure through supply line 517 and passes downward towards the reaction chamber through the number of vertical tubes 519. NH_3 vapor then exits the vertical tubes, or optionally through distributed ports in which each vertical tube is lined to a group of distributed ports,, and passes around lip 511 of the plenum. Thereby, NH_3 vapor moves towards the susceptor in a laminar flow substantially uniform across the width of the reaction chamber. Flow through each vertical tube is controlled by a separate valve mechanism 509 all of which are externally adjustable 213. The plenum also includes tubes for conducting temperature-control fluids, e.g., GALDEN™ fluid having temperatures controlled so that the plenum structures through which NH_3 passes are maintained within the above-described temperature ranges and so that plenum structure adjacent to O-ring 503 are maintained within the operational range for the sealing materials used in the O-ring. As noted, the preferred material for the O-ring is the same as that mentioned above for other o-rings. Temperature control tube 505 is visible (a corresponding

tube is also visible below port 315) adjacent to O-ring 503. In typically operation, this tube serves to cool the O-ring so that it remains within its operational range.

Gate valve 413 advantageously is an embodiment of the above-described gate valve of this invention. This gate valve includes a number of gas inlet ports 515 as well as serving to isolate the reaction and transfer chambers. It is opened and closed to provide controlled access for wafers and substrates between the transfer chamber and the reaction chamber through port 315. It is illustrated in a closed position in which it is sealed to face plate 415 by O-ring 507. In preferred embodiments, gas inlet ports 515 are used to inject purge gases, e.g., N_2 . Their size and spacing, which here is denser near the edge portions of the gate valve (and reaction chamber) and sparser at the central portions of the gate valve (and reaction chamber), are designed to improve the uniformity in composition and velocity of the process gases as they flow across the susceptor and build a purge gas curtain along the side walls of the chamber to prevent $GaCl_3$ gas from flowing underneath the susceptor to avoid undesired deposition of GaN in this location.

The temperature of the exposed face of gate valve 413 can be raised by providing heated purge gases. For example, heated N_2 can be circulated in passageways internal to gate valve 413 and then out through ports 515 in the exposed face of this gate valve. The temperature of the sealing portions of gate valve 413 and of reactor member 415 can be lowered by the cool fluid circulating in passageway 505. Although, this cool fluid primarily cools O-ring 503 between the reactor and the plenum, by conduction it can secondarily cool O-ring 507 between gate valve 413 and member 415. Optionally, further cooling of O-ring 507, if necessary, can be provided by additional passageways for cool fluid in member 415. Preferably, thermocouples (not illustrated) can be placed on and around the gate valve so that the heating and cooling mechanisms can be controlled.

Generally, for deposition of high quality epitaxial layers the inlet manifold and port structures cooperate to provide a process gas flow that is substantially laminar (thus non-turbulent) and that is substantially uniform in velocity and composition. The substantially laminar and uniform flow should extend longitudinally up to and over the susceptor and transversely across the reaction chamber (or at least across the surface of the susceptor). Preferably, process gas flows in the reaction chamber are uniform in velocity and composition across the chamber to at least 5%, or more preferably 2% or 1%. Composition uniformity means uniformity of the III/V ratio (i.e., $GaCl_3/NH_3$ ratio). This is achieved by: first, designing the process gas inlet ports to provide an already approximately uniform flow of

process gases through the reaction chamber; and second, by designing selective injection of carrier gases to cause the approximately uniform flow to become increasingly uniform. Control of flow downstream from the susceptor is less important.

Numerical modeling of the gas flow dynamics of the particular preferred embodiment has determined a preferred process gas inlet port configuration so that a substantially uniform flow is produced. Guidelines for total process gas flow rates are established according to the selected GaN deposition conditions and rates needed for intended sustained, high-throughput operation. Next, within these overall flow guidelines, insert 327 and slit 329 have been designed so the modeled GaCl_3 flow into the reaction chamber is substantially uniform across the reaction chamber. Also, modeling of intended GaCl_3 flows has indicated that after the NH_3 vapor emerges around lip 511 into the reaction chamber, this flow also becomes substantially uniform across the reaction chamber. Further, valves 509 can be controlled to ameliorate non-uniformities that may arise during operation.

Further, guided by numerical modeling, secondary carrier gas inlets have been added to increase the uniformity of the primary-process gases flows. For example, in the particular preferred embodiment, it has been found that supply of purge gases through gate valve 413 provides improvement by preventing accumulation of high concentrations of GaCl_3 vapor between the face of gate valve 413 and lip 511 (i.e., the regions enclosed by face plate 415). Also, it has been found that arranging inlets to provide greater carrier gas flow at the edges of the reaction chamber and lesser purge gas flow at the center also improves uniformity of composition and velocity of flow at the susceptor and better maintains the reactive gas above the surface of the susceptor.

EXAMPLE

The invention is now compared to a standard or conventional HVPE system to illustrate the advantages and unexpected benefits that are provided when conducting HVM of Group III-V material according to the invention. Prior to setting forth this comparison and by way of introduction, conventional HVPE systems are first briefly described in relevant part.

A conventional HVPE system consists of a hot-wall tube furnace usually fabricated of quartz. The Group III precursor is formed in-situ in the reactor by flowing HCl over a boat holding the Group III metal in a liquid form. The Group V precursor is supplied from external storage, e.g., a high pressure cylinder. Conventional HVPE has been used for the growth of arsenide, phosphide and nitride semiconductors. For the growth of GaN, the Group III source

is typically molten Ga in a quartz boat (with which the HCl reacts to form GaCl), and the Group V source is usually ammonia gas.

In more detail, the quartz tube can be oriented either vertically or horizontally. The surrounding furnace is usually of a resistive type with at least two temperature zones: one for maintaining the Group III metal at a temperature above its melting point; and the other for maintaining the substrate/wafer at a sufficiently high temperature for epitaxial growth. The Group III-metal source equipment including a boat for liquid Group III metal, the substrate/wafer holder, and gas inlets are placed and arranged in one end of the quartz furnace tube; the other end serves for exhausting reaction by-products. All this equipment (or at least that which enters the furnace tube) must be fabricated of quartz; stainless steel cannot be used. Most reactors process only one wafer at a time at atmospheric pressure. Multiple wafers must be arranged in a reactor so that the surfaces of all wafers are directly in line of the gas flow in order to achieve uniform deposition.

Wafers are loaded by first placing them on a substrate support and then by positioning the substrate support into a high-temperature zone in the quartz furnace tube. Wafers are unloaded by removing the support from the furnace and then lifting the wafer off the support. The mechanism for positioning the substrate support, e.g., a push/pull rod, must also be fabricated of quartz since they are also exposed to full growth temperatures. Supported wafers, the substrate support, and the positioning mechanism must be positioned in the usually hot reactor tube with great care in order to prevent thermal damage, e.g., cracking of the wafers and/or substrate support. Also, the reactor tube itself can be exposed to air during wafer loading and unloading.

Such conventional HVPE reactors are not capable of the sustained high volume manufacturing that is possible with the HVM methods and systems of this invention for a number of reasons. One reason is that the reactors of this invention require less unproductive heating and cooling time than do conventional HVPE reactors because they can have considerably lower thermal masses. In the reactors of this invention, only the susceptor (substrate/wafer support) needs to be heated, and it is heated by rapidly-acting IR lamps. Heating and cooling can thus be rapid. However, in conventional HVPE reactors, the resistive furnace can require prolonged heating and (especially) cooling times, up to several to tens of hours. During such prolonged heating and cooling times, this system is idle, and wafer production, reactor cleaning, system maintenance, and the like must be delayed. Furthermore, despite risks of thermal damage, wafers are usually placed in and removed from the reactor

when it is near operating temperatures to avoid further heating and cooling delays. For these reasons, the systems and methods of this invention can achieve higher throughputs than can conventional HVPE systems.

Another reason limiting the throughput of conventional HVPE systems is that such systems require considerably more reactor cleaning than do the reactors of this invention. Because all internal components of conventional HVPE reactors are heated by the external resistive furnace, III-V material can grow throughout the inside of the reactor, and not only on the substrate where it is desired. Such undesired deposits must be frequently cleaned from the reactor or else they can form dust and flakes which contaminate wafers. Cleaning requires time during which the reactor is not productive.

Also, the Group III precursor is inefficiently used; most is deposited on the interior of the reactor; a small fraction is deposited on the substrate wafer as desired; and little or none appears in the reactor exhaust where it might be recycled for reuse. The Group V precursor is also inefficiently used, and excess can react with unused HCl to form chlorides (e.g., NH_4Cl) that can deposit on cold areas downstream of the reaction zone. Such chloride deposits must also be cleaned from the reactor.

In contrast, the reactors of this invention have temperature controlled walls so that little or no undesired growth of Group III-V material occurs. Reactors of this invention can be more productive since unproductive cleaning and maintenance either can be shorter, or need not be as frequent, or both. For these reasons also, the systems and methods of this invention can achieve higher throughputs than can conventional HVPE systems.

Another reason limiting the throughput of conventional HVPE systems is that their conventional internal Ga sources require recharging (with liquid Ga or other Group III metal) considerably more frequently than do the external Ga sources of this invention of this invention (which are recharged with the Ga precursor GaCl_3). The external source of this invention delivers a flow of Ga precursor that can be controlled in both rate and composition at maximum sustained rates up to approximately 200 gm/hr or greater. Since the capacity of the external source is not limited by reactor geometry, it can be sufficient for many days or weeks of sustained production. For example, an external source can store up to many tens of kilograms of Ga, e.g., approximately 60 kg, and multiple sources can be operated in series for essentially unlimited sustained production.

In conventional HVPE systems, the Ga source has a strictly limited capacity. Since the source must fit inside the reactor and can be no larger than the reactor itself, it is believed

that an upper limit to a conventional source is less than 5 kg of Ga. For example, for 3 kg of Ga, a boat of approximately 7x7x20 cm filled with liquid Ga 4 cm deep is required.

Disclosure of such a large Ga boat has not heretofore been found in the prior art. Further the rate and composition of the source cannot be well controlled, because the Ga precursor (GaCl)
5 is formed in situ by passing HCl and over the liquid Ga in the Ga source boat inside the reactor. The efficiency of this reaction is dependent upon reactor geometry and exact process conditions, e.g., the temperature in the source zone, and various efficiency values from 60% to over 90% have been reported. Furthermore, as the level of the Ga decreases and as the Ga source ages, the flux of GaCl to the deposition zone can vary even with a constant process
10 conditions. For these reasons also, the systems and methods of this invention can achieve higher throughputs that can conventional HVPE systems.

Another reason limiting the throughput of conventional HVPE systems is that heretofore their construction is not standardized, and in fact such systems are often individually designed and fabricated for specific users. Lack of standardization leads to, for
15 example, slow and complex maintenance. Because they can often include complex and fragile quartz components that are difficult to work with, such reactors are time-consuming to disassemble and reassemble. In particular, the Group III source zone is intricate as it contains a separate quartz inlet for HCl, a quartz boat positioned adjacent to the HCl inlet, a separate quartz inlet for the Group V precursor (which must be kept separate from the Group III
20 precursor), and a possible additional quartz inlet for a carrier gas. In contrast, the systems and methods of the present invention are to a great extent adaptations of tested and standardized designs known for Si processing, which have been optimized for efficient operation and maintenance and which include commercially-available components. For example, the particular preferred embodiment includes a Group III source zone with a gate valve and Group
25 III precursor plenum and inlet ports partially fabricated from metal. The gate valve requires only a short time to open and close, and the Group III precursor plenum and inlet ports are considerably less fragile. For these reasons also, the systems and methods of this invention can achieve higher throughputs that can conventional HVPE systems.

The qualitative design choices that differentiate systems of this invention from
30 conventional HVPE systems leads to surprising quantitative benefits in epitaxial growth efficiencies, reactor utilizations and wafer production rates, and precursor utilization efficiencies. These surprising quantitative benefits are reviewed below using the data in Tables 1, 2, and 3, which compare a conventional HVPE system designed to handle one 100

mm diameter substrate and including a reactor tube of about 20 cm in diameter and about 200 cm in length with a corresponding system of this invention.

Considering first achievable epitaxial growth efficiencies, the data of Table 1 demonstrate that the HVM systems of this invention can be considerably more efficient than conventional HVPE systems.

TABLE 1 – Epitaxial growth efficiencies

Epitaxial growth efficiencies		Conventional HVPE	HVM
Reactor Information			
Wafer diameter	cm	15	15
Reactor length	cm	200	
Reactor diameter	cm	20	
Hot zone length	cm	40	
# wafers processed simultaneously		1	1
Reactor production times			
- wafer load/unload time			
Pull/push rate	cm/min	2	
Total pull and push length	cm	160	0
Total pull and push time	min	80	2
Wafer load/unload time	min	9.5	2
Total load/unload time	min	89.5	3
Operation overhead	%	10%	10%
Total load/unload time in cont. operation	min	52.0	2.2
- epitaxial growth time			
Time to grow template	min	0	0
Growth rate	um/hr (um/min)	200 (3.3)	200 (3.3)
Layer thickness	um	300	300
Time to heat and cool	min	0	6
Time to grow layer	min	90	90
Operation overhead	%	10%	10%
Total growth time	min	99	106
Total wafer-in-reactor time	min	151.0	107.8
Reactor utilization (R.U.)			
R. U. - growth time/wafer-in-reactor time	%	66%	98%

Epitaxial growth efficiencies can be represented by the ratio of the actual epitaxial growth

times to the sum of the actual epitaxial growth times and the reactor load/unload times. It can

be seen that the HVM systems and methods of this invention can be loaded/unloaded significantly faster than can conventional HVPE systems, and thus can achieve higher epitaxial growth efficiencies. It is also expected that in actual operation, the external Ga sources of this invention will allow sustained operation for considerably longer periods than possible with conventional systems.

Because, in conventional HVPE system, the reactor is maintained at near deposition temperature between runs, the substrate must be pulled from or pushed into the reactor at a slow enough rate to avoid thermal damage. Assuming that distance of the substrate holder from the reactor inlet is about 80 cm and a pull rate of no more than 2 cm/min to avoid thermal damage, about 40 min. are required to pull the substrate from and also to push the substrate into the reactor. Further, once the substrate and wafer are positioned in the reactor, up to 10 min can be required for thermal stabilization, reactor purge, and set-up of process gasses. (With load locks the purge and gas setup might require 5 minutes each; without load locks, setup would be much longer.) Thus, the total load/unload time is about 90 min, or 52 min in continuous production (where some times would be shared equally between two successive runs).

In contrast, in the HVM systems of this invention, wafers can be rapidly loaded/unloaded at lower temperatures without risk of thermal damage thus eliminating extended wafer positioning times. Because of their low thermal mass and IR-lamp heating, reactors used (and specifically the susceptor and wafer in such reactors) in the HVM systems and methods of this invention can be rapidly cycled between higher deposition temperatures and lower temperatures loading/unloading temperatures. Therefore, the HVM systems and methods of this invention achieve considerably shorter loading/unloading times than are possible in conventional HVPE reactors.

Once loaded and assuming Ga precursor sources used in conventional HVPE systems are able to maintain an adequate mass flow rate of precursor, actual epitaxial growth times of conventional systems and of the systems of this invention are of approximately the same magnitude. However, it is expected that the Ga precursor source used in the HVM systems and methods of this invention has significant advantages over Ga precursor source used in convention HVPE systems, so that in actual operation the systems and methods of this invention will achieve relative epitaxial growth efficiencies even greater than the efficiencies presented in Table 1.

For example, even if capable of adequate mass flow for an initial period, it is unlikely that convention Ga sources can sustain adequate mass flow for extended periods.

Conventional HVPE systems generate Ga precursor in-situ to the reactor by the passing HCl gas over metallic gallium in a liquid form. Because the efficiency of this process depends

5 strongly on reactor geometry and process conditions (e.g., from about 60% to over about 90% depending on Ga temperature), the actual mass flow of Ga precursor (GaCl) will also vary.

Further, as the level of the Ga decreases and the Ga source ages, the flux of Ga precursor can vary even with a constant process conditions (e.g., constant temperature and input HCl flux).

Further, conventional Ga sources (in particular the liquid Ga boat) must be within the reactor,

10 and their capacities are thus constrained by reactor geometry. The largest boat believed to be reasonably possible (and not believed to be disclosed in the known in the prior art) in a

conventional HVPE system could hold no more than about approximately 3 to 5 kg and would be approximately 7x7x20 cm in size and be filled 4 cm deep with liquid Ga.

In contrast, the HVM systems and methods of this invention employ an external Ga
15 source which can provide constant, unvarying flow of Ga precursor at up to 200 gm of Ga/hr and greater (sufficient to support growth rates in excess of 300 um/hr) that can be sustained for extended periods of time. First, this source can provide GaCl₃ vapor in a manner so that the Ga mass flux can be measured and controlled even during epitaxial growth. Second, this external Ga source is capable of sustained, uninterrupted operation because Ga precursor is
20 supplied from a reservoir holding 10's of kilograms of precursor. Additionally, multiple reservoirs can be operated in series for effectively unlimited operation.

In summary, relative epitaxial growth efficiencies can be summarized by reactor utilization (R.U.) defined by the fraction of the time that a wafer is in the reactor during which actual growth is occurring. It is seen that the HVM systems and methods of this invention
25 achieve such a R.U. of about 95% or more, while conventional HVPE systems can achieve such a R.U. of no more than about 65%. And it is expected that the HVM systems and methods of this invention will achieve even greater relative epitaxial growth efficiencies in actual operation.

Next considering first achievable reactor utilizations and wafer production rates, the
30 data of Table 2 demonstrate that the HVM systems of this invention can be more efficient than conventional HVPE systems.

TABLE 2 - Reactor utilizations and achievable wafer production rates

Reactor maintenance times and wafer production rates		Conventional HVPE	HVM
- in-situ reactor cleaning time			
# runs between in-situ cleaning		5	5
Time to open/close reactor	min	26.6	2
Total thickness to be etched	um	1500	300
Etch rate	um/min	8	8
Etch time	min	187.5	18.8
bake time	min	30	15
Time to load Ga with in-situ etch	min	45	0.0
Operation overhead	%	18%	15%
Total in-situ cleaning time	min	339.8	41.1
- ex-situ reactor cleaning time			
# runs between ex-situ cleaning		15	15
time to close reactor after unloading	min	13.3	1.0
time to cool reactor	min	180	20
time to take reactor apart	min	120	120
time to put reactor back together	min	180	120
time to leak check and other	min	45	45
Time to load Ga with ex-situ etch	min	10	0
time to heat reactor	min	75	20
Wafer testing time	min	60	60
Preventive maintenance	min	120	120
Operation overhead	%	25%	20%
Total ex-situ cleaning time	min	959.2	571.2
Reactor utilization (R.U.) and wafer production rate			
R. U. - wafer-in-reactor time/total use time	%	59%	76%
R. U. - growth time/total use time	%	39%	75%
# runs (wafers)		15	15
total use time for #runs (wafers)	min	3734	1996
# wafers/hour		0.24	0.45
# hours/wafer		4.15	2.22
# wafers/24 hours		5.8	10.8

Reactors must be periodically taken out of production for cleaning and preventive maintenance. Since the HVM systems and methods of this invention can be rapidly cleaned and maintained, they can achieve higher reactor utilizations and wafer production rates than can conventional HVPE systems.

During operation, materials grow on undesired locations in the reactor, e.g., on the reactor walls and on other internal reactor components, and excessive growth of these materials can cause problems, e.g., wafer contamination. Cleaning is required to remove these undesired materials, and can be performed either in-situ, that is without disassembling the reactor, or ex-situ, after disassembling the reactor. In-situ cleaning is often performed by etching undesired deposits with HCl. After a number of in-situ etchings or cleanings, more thorough ex-situ cleaning is advantageous.

HVM systems of this invention require considerably less in-situ cleaning time than conventional HVPE systems. The reactors of this invention have walls with controlled lower temperatures so that little material deposits thereon during wafer production. In contrast, conventional HVPE reactors operate at higher deposition temperatures so that the same amount of material grows on reactor walls and internal reactor parts as grows on the wafers and substrates. Table 2 presents a scenario which assumes that no more than 1.5 mm of unwanted GaN can be allowed to deposit on reactor walls and internal reactor parts.

For conventional HVPE systems, in-situ cleaning is required every 5 runs, during which 1.5 mm of unwanted GaN (300 um per run and) will have grown on the reactor interior. In contrast, if in-situ cleaning of the reactors of this invention is also performed every 5 runs, only a nominal amount (e.g., 20% or less of the amount that will have grown in conventional HVPE systems) of GaN will have grown on the reactor interior. (In fact, in-situ cleaning of the HVM systems of this invention could reasonably be delayed to only every 15 runs.) Therefore, in-situ cleaning times of conventional HVPE reactors are at least 5 times (and up to 15 times) longer than the in-situ cleaning time of the HVM reactors of this invention.

Also, the HVM systems of this invention require considerably less ex-situ cleaning time than conventional HVPE systems. First, these HVM systems have significantly shorter cooling/heating times which must precede and follow, respectively, ex-situ cleaning. Also, their disassembly/cleaning/reassembly times are similar to the shorter times known for Si processing systems, because the HVM systems and methods of this invention comprise commercially available designs and components already known for Si processing. The designs and components incorporated from Si processing systems include: rapidly-acting reactor gates, fully automated wafer handling with cassette-to-cassette loading, the ability to perform hot load/unload, separate cooling stages, in-situ growth rate monitoring and load locks to prevent exposure of the reactor to atmosphere.

And, as already discussed, the Ga precursor sources, i.e., the Ga boat, used in conventional HVPE systems must be periodically recharged in order both to maintain constant precursor flow and also because of their limited capacity. This precursor recharging, which can be performed during cleaning, further lengthens cleaning times of these conventional systems. In contrast, the external Ga sources of the HVM systems and methods of this invention can operate with little or no interruption for extended periods of time.

In summary, reactor maintenance times can be summarized by a further R.U. and a wafer production rate. This second R.U. represents the ratio of the time that a wafer is in the reactor to the sum of the times that a wafer is in the reactor plus the cleaning/maintenance times. It can be seen that the HVM system and methods of this invention achieve a R.U. of about 75% or more, while conventional HVPE systems can achieve such a R.U. of no more than about 60%.

Relative system efficiencies can be represented by wafer production rates, which can be derived by dividing a number of wafers produced by the total time required to produce these wafers. Since a complete cycle of wafer production runs, in-situ cleanings, and ex-situ cleanings, rates comprises 15 runs (according to the assumptions of Tables 1 and 2), these rates are determined by dividing 15 by the total time for producing 15 wafers (including load/unload time, in-situ cleaning time, in-situ cleaning time, maintenance time, and source recharge time). It can be seen that the total time the HVM systems and methods of this invention require to produce 15 wafers (runs) is considerably shorter than the total time required by convention HVPE systems. Therefore, the systems and methods of this invention achieve an approximately 2 fold throughput improvement over the prior art. As discussed above, a greater throughput improvement is expected during actual operation.

Lastly, considering comparative precursor efficiencies, the HVM systems and methods of this invention utilize precursors, especially Ga precursors, more efficiently than conventional HVPE systems. This is exemplified by the data in Table 3.

TABLE 3 - Precursor utilizations

Precursor utilization		Conventional HVPE	HVM
- ammonia (both processes)			
Ammonia Flow	slpm	14	10
Total ammonia flow time	min	132.0	97.7
Total ammonia for 90 min. run	mole	82.5	43.6
- HCl (convention HVPE)			
Moles of HCl /min during run	mole/min	0.024	
Liters HCl used in run	liter	51.2	
- gallium (convention HVPE)			
Input V/III ratio		30	
Moles/min of ammonia during run	mole/min	0.6250	
Moles/min of Ga required by ammonia flow	mole/min	0.0208	
Conversion of GaCl ₃ to GaN	%	95%	
Actual moles/min of Ga used in run	mole/min	0.0219	
Additional moles of Ga	%	10%	
moles of Ga/min for run	mole/min	0.024	
Weight of Ga/min for run	gm/min	1.76 gm Ga/min; 100 gm Ga/hr	
Weight of Ga per run	gm	151.4	
- gallium (HVM)			
Input V/III ratio			30
moles of ammonia/min during run	mole/min		0.4464
moles/min of Ga to meet V/III	mole/min		0.0149
Conversion of GaCl ₃ to GaN	%		95%
moles of GaCl ₃ dimer/min required to meet V/III	mole/min		0.0082
Additional moles of GaCl ₃ dimer	%		10%
Total moles GaCl ₃ dimer for run	mole		0.82
Atomic weight GaCl ₃ dimer	gm/mole		352.2
Total weight of GaCl ₃ dimer for run	gm		287.4
Percent of GaCl ₃ dimer that is Ga	%		40%
Weight of Ga for run	gm		114
Weight of Ga/hour for run	gm		75 gm Ga/hr
Ga utilization	%	21%	25%
Utilization with Ga recycling (est.)	%	27%	80%

Ga utilization is determined in Table 3 by, first, considering that a conventional HVPE system suitable for a 15 cm wafer can be expected to use approximately 14 slpm (standard

liters per minute) of ammonia. Assuming a V/III ratio of 30 and a 95% conversion of the Ga precursor into GaN, the conventional system can be expected to use approximately 1.8 gm/min of Ga. A 90 minute run sufficient to grow 300 um of GaN at 200 um/hr therefore requires about 151 gm of Ga. Since there is about 31 gm of Ga in a 300 um layer on a 15 cm wafer, the Ga efficiency of the conventional HVPE reactor is approximately 21% (= 31/151). Since most of the remaining 120 gm (= 151-31) is deposited on the insides of the reactor, little is thus unavailable recycling and reuse. It is expected that even with recycling and reuse of Ga exhausted from the reactor, the Ga efficiency of the conventional HVPE reactor is no more than approximately 25%.

In contrast, HVM systems and methods can be expected to use a lower ammonia flow (e.g., 10 slpm) and therefore a lower Ga flow and a lower total Ga required for a 15 cm wafer (e.g., 114 gm). Therefore, the HVM systems and methods of this invention can achieve Ga efficiencies of 27% (= 31/114) without recycling and reuse and up to perhaps 80% or greater Ga efficiency with recycling and reuse of Ga exhausted from the reactor. Additionally, since little of the remaining 83 gm (= 114-31) is deposited on the insides of the reactor, most of this unused Ga appears in the reactor exhaust where it is available recycling and reuse. It is expected that with recycling and reuse of exhaust Ga, the Ga efficiency of the HVM systems and methods of this invention can reach 80% or greater.

The preferred embodiments of the invention described above do not limit the scope of the invention, since these embodiments are illustrations of several preferred aspects of the invention. Any equivalent embodiments are intended to be within the scope of this invention. Indeed, various modifications of the invention in addition to those shown and described herein, such as alternate useful combinations of the elements described, will become apparent to those skilled in the art from the subsequent description. Such modifications are also intended to fall within the scope of the appended claims. In the following (and in the application as a whole), headings and legends are used for clarity and convenience only.

A number of references are cited herein, the entire disclosures of which are incorporated herein, in their entirety, by reference for all purposes. Further, none of the cited references, regardless of how characterized above, is admitted as prior art to the invention of the subject matter claimed herein.

THE CLAIMS

What is claimed is:

- 5 1. A method for forming a monocrystalline Group III - V semiconductor material which comprises:
- reacting an amount of a gaseous Group III precursor as one reactant with an amount of a gaseous Group V component as another reactant in a reaction chamber under conditions sufficient to manufacture the semiconductor material,
- 10 introducing the reactants so that they react at a predetermined location in the reaction chamber adjacent and above one or more substrates to deposit semiconductor material thereon, and
- injecting one or more purge gas streams to assist in directing at least one of the reactants to the predetermined location.
- 15 2. The method of claim 1 wherein the gaseous Group III precursor is continuously provided at a mass flow of at least 50 g Group III element/hour for a time of at least 48 hours.
3. The method of claim 1 which further comprises injecting the purge gas streams
- 20 through a plurality of apertures in a gate valve, the gate valve being closable to seal an inlet port of the reaction chamber and being openable to allow transfer of materials between the reaction chamber interior and exterior through the inlet port.
4. The method of claim 3 which further comprises sufficiently controlling the
- 25 temperature of portions of the gate valve adjacent to a seal between the gate valve when closed and the reaction chamber in order to avoid thermal deterioration of the seal during operation.
5. The method of claim 4 wherein the gate valve is temperature controlled by
- 30 passing heat exchange fluids through passages that are conductively-coupled to the gate valve.
6. The method of claim 3 which further comprises sufficiently heating portions of the gate valve exposed to the reaction chamber interior when closed in order to avoid condensation of and/or unwanted reaction between gases in the reactor.

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7. The method of claim 6 wherein the gate valve is heated by passing a heated fluid through one or more passageways internal to the gate valve.

8. The method of claim 6 wherein the gate valve is sufficiently heated so that the temperature of the exposed portions are greater than either or both of a condensation temperature of the Group III precursor and a sublimation temperature of a product of a Group III-Group V reaction.

9. A gate valve assembly configured to be used for reversibly sealing a material-transfer port of a CVD reaction chamber, the assembly comprising:

a gate valve that is closable to seal the transfer port and openable to allow transfer of materials through the inlet port; and

a temperature control that maintains gate valve temperatures in selected ranges of temperature during reaction-chamber operation.

10. The assembly of claim 9 wherein temperature control further comprises one or more heating elements for sufficiently heating the portions of the gate valve exposed to the reaction chamber interior when closed in order to avoid condensation of and/or unwanted reaction between gases in the reactor.

11. The assembly of claim 10 wherein the heating elements comprise one or more of a radiant-heating element external to the gate valve and a passage internal to the gate valve for heated fluids.

12. The assembly of claim 11 further comprising a seal between the closed gate valve and the reaction chamber, and wherein temperature control further comprises one or more cooling elements for sufficiently cooling portions of the gate valve adjacent to the seal to avoid thermal deterioration of the seal during operation.

13. The assembly of claim 12 wherein the cooling elements comprise one or more passages for cooled fluids that are conductively-coupled to the gate valve.

14. The assembly of claim 11 wherein the gate valve further comprises a plurality of apertures configured to inject gas streams into the reaction chamber during operation.

15. The assembly of claim 14 wherein the apertures are in a spaced relation with the spacing between the apertures in a central portion being greater than the spacing of the apertures in other portions.

5 16. The assembly of claim 14 wherein the apertures are in a spaced relation with the substantially uniform spacing between the apertures.

17. A system for manufacture of a monocrystalline Group III-V semiconductor material, which comprises:

10 a source of a Group III precursor for use as one reactant;
a source of Group V component for use as another reactant;
a reaction chamber that receives the Group III precursor and Group V component for reaction therewith under conditions sufficient to form the Group III-V semiconductor material, the reaction chamber having
15 apertures for introducing the reactants into the reaction chamber so that they meet and react at a predetermined location in the reaction chamber adjacent and above one or more substrates to deposit semiconductor material thereon,
apertures for injecting one or more purge gas streams, and
a loading port through which semiconductor materials can be transferred
20 between the interior and exterior of the reactor;
a gate valve assembly for sealing the loading port, the assembly comprising a seal between the gate valve and reactor and a temperature control for controlling the temperature of the gate valve so as to avoid both condensation of and/or unwanted reaction between gases in the reactor and also thermal deterioration of the seal.

25 18. The system of claim 17 wherein the gate valve further comprises a plurality of apertures through which the purge gas streams are injected into the reaction chamber in a manner that at least partially directs one reactant to the predetermined location.

30 19. The assembly of claim 17 wherein the temperature control further comprises one or more heating elements for sufficiently heating portions of the gate valve exposed to the reaction chamber interior when closed in order to avoid condensation of and/or unwanted reaction between gases in the reactor.

20. The assembly of claim 17 further comprising a seal between the closed gate valve and the reaction chamber, and wherein the temperature control further comprises one or more cooling elements for sufficiently cooling portions of the gate valve adjacent to the seal to avoid thermal deterioration of the seal during operation.

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21. The assembly of claim 17 wherein the temperature control further comprises one or more elements for sensing temperatures of the gate valve and for providing feedback to the temperature control.

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22. The system of claim 17 wherein the reactants enter the reaction chamber as horizontal laminar flows.

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23. The system of claim 17 wherein the reaction chamber includes a floor, a ceiling, a pair of sidewalls, an open inlet, an open outlet, and one reactant entry aperture comprises a horizontal slot in the floor for introducing that reactant into the reaction chamber, with the slot configured and dimensioned to introduce the reactant and to direct it to the predetermined location for reaction with another reactant.